

Fabrication Challenges for Superconductor Electronics

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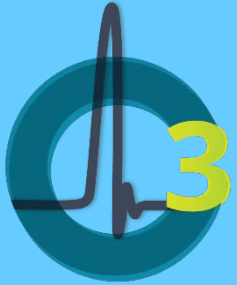
Seminar at

2019-

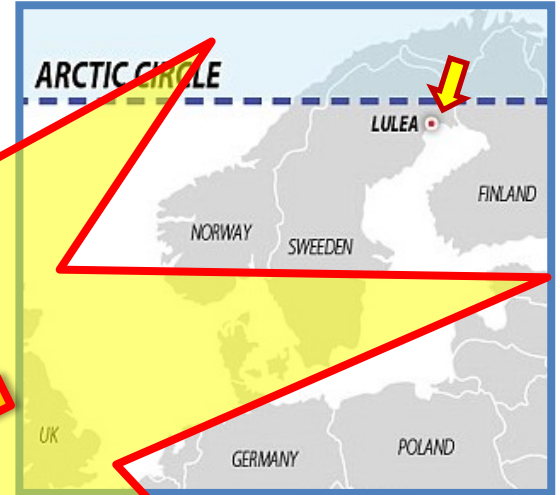
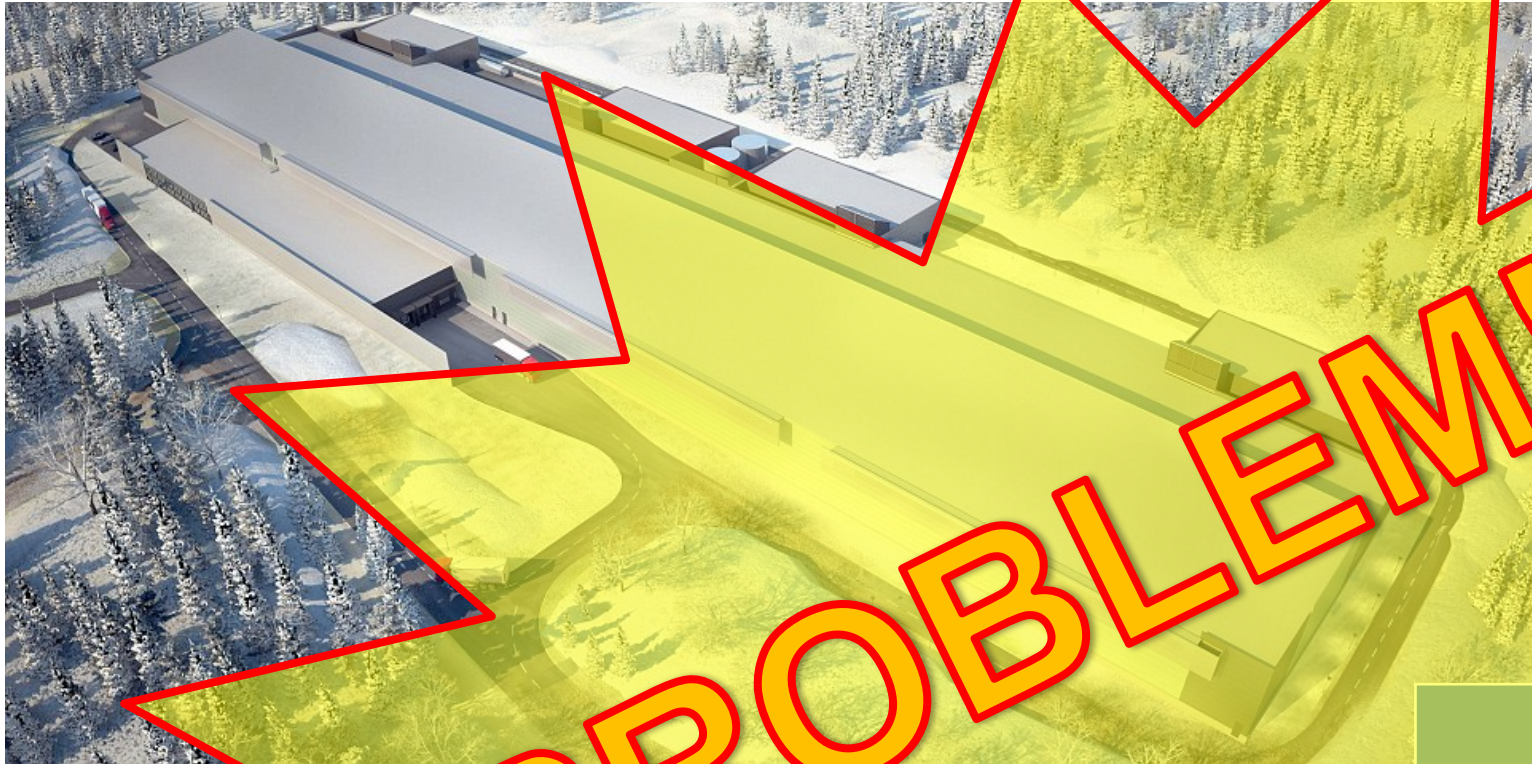




- IARPA Cryogenic Computing Complexity (C3) Program
- Related Work
- Challenges Remaining for Superconductor Electronics (SCE)
- Future Prospects



DARPA Cryogenic Computing Complexity (C3) Program



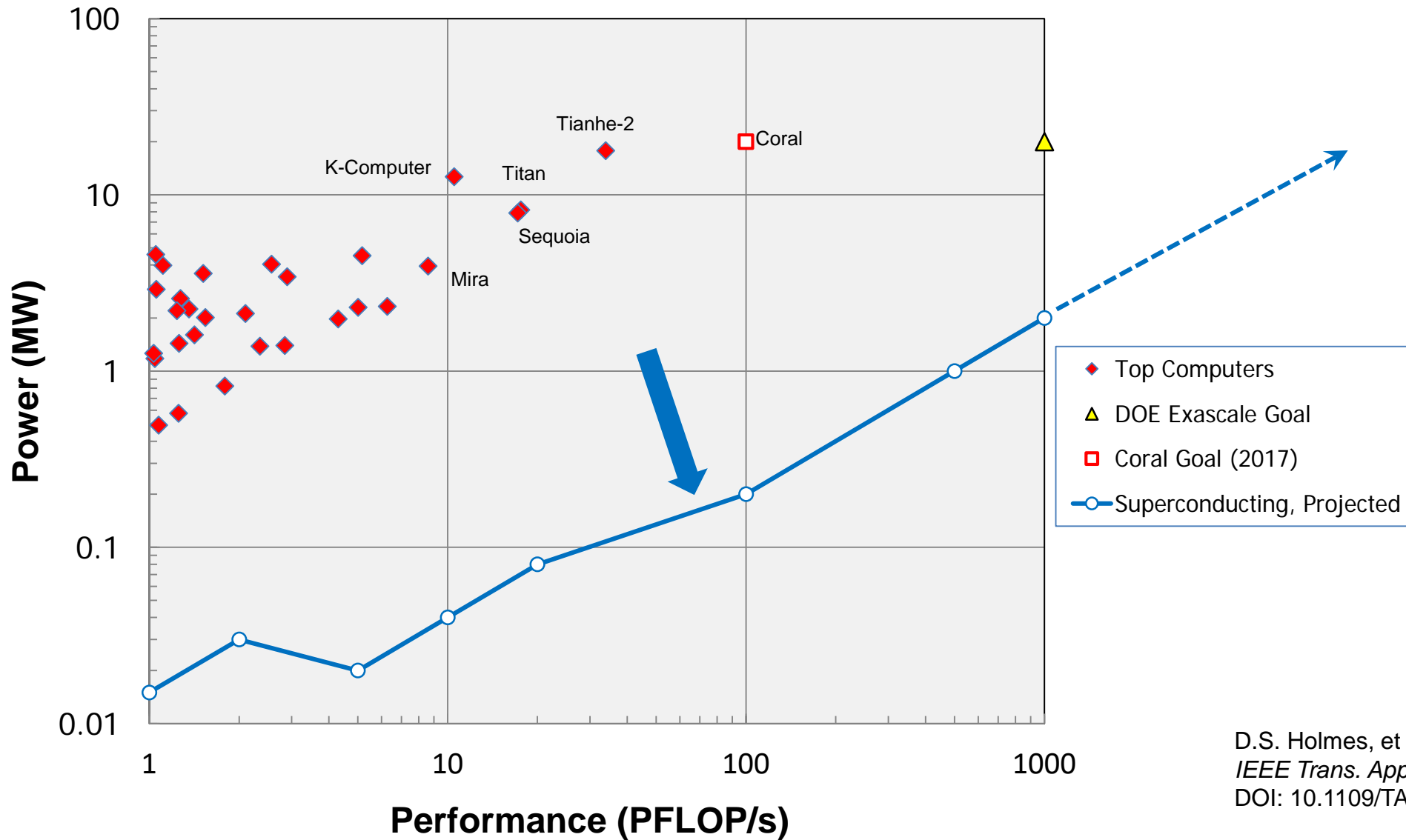
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PROBLEM!

- 2013 construction start
- Cost: ~760 M\$
- Nearby Lule River generates 9% of Sweden's electricity (~4.23 GW)
- Average annual temperature: 1.3 °C

| Specifications | |
|----------------|--|
| Performance* | 27-51 PFLOP/s |
| Memory* | 21-27 PB RAM 1900-6800 PB disk |
| Power | 84 MW avg* (120 MW max) |
| Space | 290,000 ft ² (27,000 m ²) |
| Cooling* | ~1.07 PUE |

* estimated



D.S. Holmes, et al.,
IEEE Trans. Appl. Supercond., 2013,
 DOI: 10.1109/TASC.2013.2244634



Interconnect Requirements (Superconductor HPC)

Desirable architectural metrics for supercomputers designed for floating-point-intensive applications

- Main memory:
0.1 to 1 B s/FLOP
- Main memory latency (access time):
< 100 cycles
- Main memory data access rate:
1 B/FLOP
- Input/Output data rate:
 10^{-5} to 10^{-3} B/FLOP
- Parallelism:
fewer processors is generally better

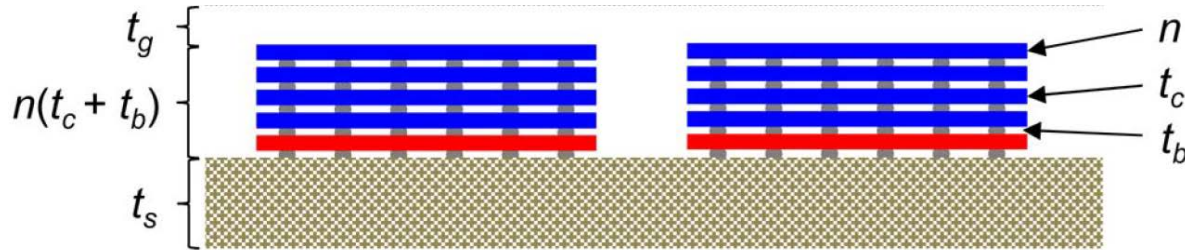
D.S. Holmes, et al.,
IEEE Trans. Appl. Supercond., 2013,
 DOI: 10.1109/TASC.2013.2244634

TABLE II
 INTERCONNECT POWER DISSIPATION AT 4 K

| | System Performance (PFLOP/s) | | | |
|-------------------------------------|------------------------------|------------------|------------------|------------------|
| | 1 | 10 | 100 | 1,000 |
| I/O data rate ^a (Tbit/s) | 0.8 | 8 | 80 | 800 |
| • Channels ^b , 20 Gbit/s | • 80 | • 800 | • 8,000 | • 80,000 |
| Power leads | c | c | c | c |
| Input data | c | c | c | c |
| Cache memory access | 18 mW | 180 mW | 1.8 W | 18 W |
| Main memory access | 9 mW | 90 mW | 0.9 W | 9 W |
| Output data | 10 mW | 100 mW | 1.0 W | 10 W |
| • Drivers, eSFQ-to-DC ^d | • 0.024 | • 0.24 | • 0.002 | • 0.024 |
| • Ribbon cable to 40 K | • 8.3 | • 83 | • 0.83 | • 8.3 |
| • VCSEL array at 40 K ^d | • 0 ^e | • 0 ^e | • 0 ^e | • 0 ^e |
| Interconnects, total | 0.1 W | 1 W | 10 W | 100 W |
| I/O budget | 0.4 W | 3 W | 30 W | 300 W |

^a Specified using the mid-range I/O data rate (10^{-4} B/FLOP)·(8 bit/B).
^b Channel capacity is 2 times the specified I/O data rate.
^c No estimate made.^d [47].
^e Vertical-cavity surface-emitting laser (VCSEL) heat load is less than refrigerator intermediate stage capacity, so no effect on 4 K capacity.

- Ranges calculated for stacks of 1 to 5 chips



- Packaged volume (V) relationship to active circuit area (A_a)

$$\left(\frac{V}{A_a}\right)_{MCM} = [t_g + t_s + n(t_c + t_b)] (f \cdot n)^{-1} \quad (3)$$

where:

- t_g 2 to 10 mm; vertical gap between stacked MCMs
- t_s 0.5 to 1 mm; thickness of the MCM substrate
- t_c 50 to 200 μm ; thickness of a circuit chip
- t_b 10 to 30 μm ; thickness added by bump bonds
- n 1 to 5; number of chips in a stack
- f 0.4 to 0.6; effective in-plane area fraction covered by chips, including MCM-to-MCM horizontal spacing

D.S. Holmes, et al., *IEEE Trans. Appl. Supercond.*, 2013.
DOI: 10.1109/TASC.2013.2244634

TABLE III
CIRCUIT AREA AND CRYOSTAT VOLUME RANGES

| | System Performance (PFLOP/s) | | | |
|---|------------------------------|----------|-----------|--------------|
| | 1 | 10 | 100 | 1,000 |
| Logic, processors ^a | 40,200 | 402,000 | 4,020,000 | 40,200,000 |
| • circuit area ^b (m ²) | 80.4 | 804 | 8,040 | 80,400 |
| • MCM volume (m ³) | 0.08-2.4 | 0.8-24 | 8-240 | 80-2,400 |
| Memory ^c (PB) | 1 | 10 | 100 | 1,000 |
| • circuit area (m ²) | 1.1e+3 | 1.1e+4 | 1.1e+5 | 1.1e+6 |
| • MCM volume (m ³) | 1.1-33 | 11-330 | 110-3,300 | 1,100-33,000 |
| Interconnect channels ^d | 80 | 800 | 8,000 | 80,000 |
| • circuit area (m ²) | 1.2 | 12 | 120 | 1,200 |
| • MCM volume (m ³) | 0.002-0.06 | 0.02-0.6 | 0.2-6 | 2-60 |
| Other ^e (m ³) | 0.1-3.3 | 1-33 | 10-330 | 100-3,300 |
| System volume | | | | |
| • high (m ³) | 39 | 390 | 3,900 | 39,000 |
| • low (m ³) | 1.3 | 13 | 130 | 1,300 |

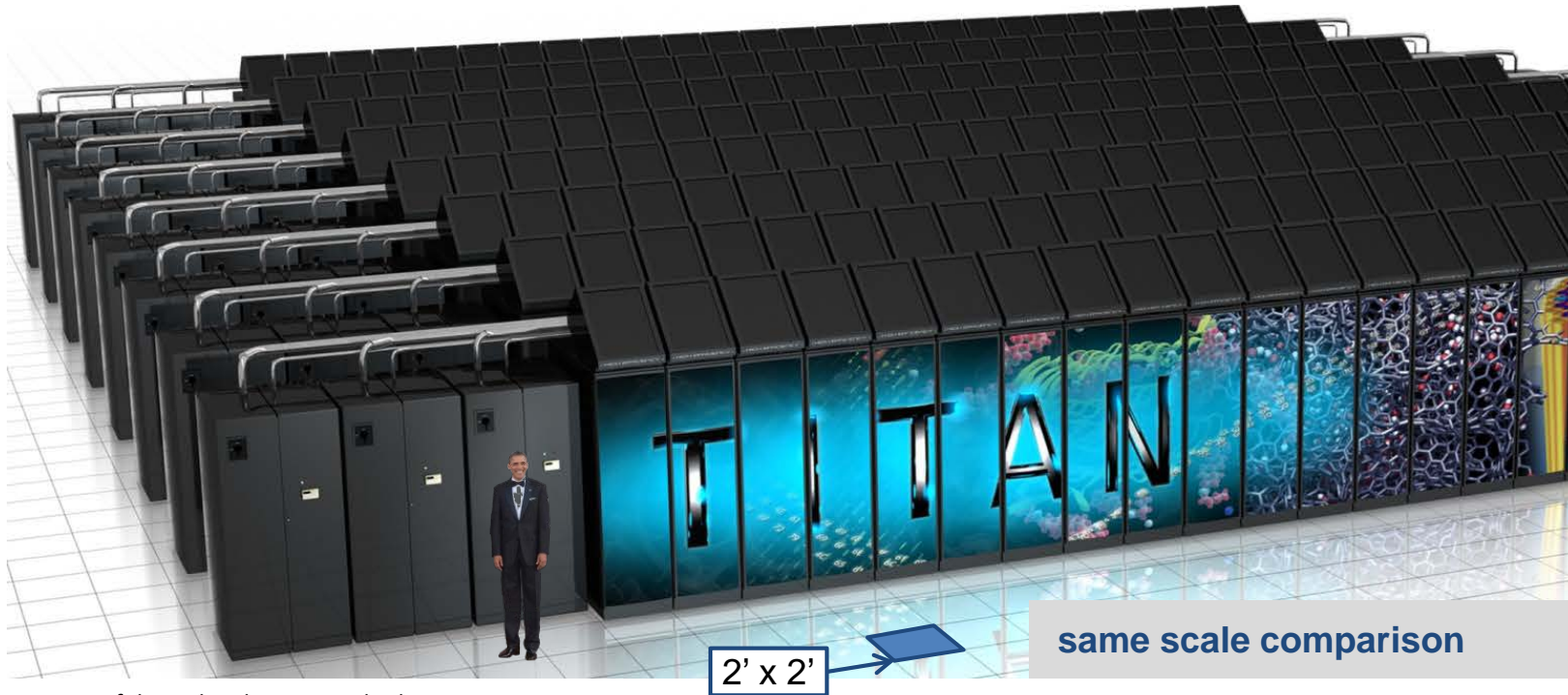
^a RQL, $I_c = 25 \mu\text{A}$, 8.3 GHz [48].

^b 2×10^7 Josephson junctions per processor, 10^{10} JJ/m².

^c Josephson MRAM [48], 1 byte per FLOP/s, 900 GB/m².

^d Specifications in Table II, circuit area is 5% of logic area.

^e Cryostat + structure estimated as 10% of total MCM volume.



Courtesy of the Oak Ridge National Laboratory, U.S. DoE



Courtesy of IARPA

| | Titan at ORNL | Superconductor Supercomputer | |
|--------------------|--|---|-------|
| Performance | 17.6 PFLOP/s (#2 in world*) | 20 PFLOP/s | ~1x |
| Memory | 710 TB (0.04 B/FLOPS) | 5 PB (0.25 B/FLOPS) | 7x |
| Power | 8,200 kW avg. (not included: cooling, storage memory) | 80 kW total power (includes cooling) | 0.01x |
| Space | 4,350 ft ² (404 m ² , not including cooling) | ~200 ft ² (19 m ² , includes cooling) | 0.05x |
| Cooling | additional power, space and infrastructure required | All cooling shown | |

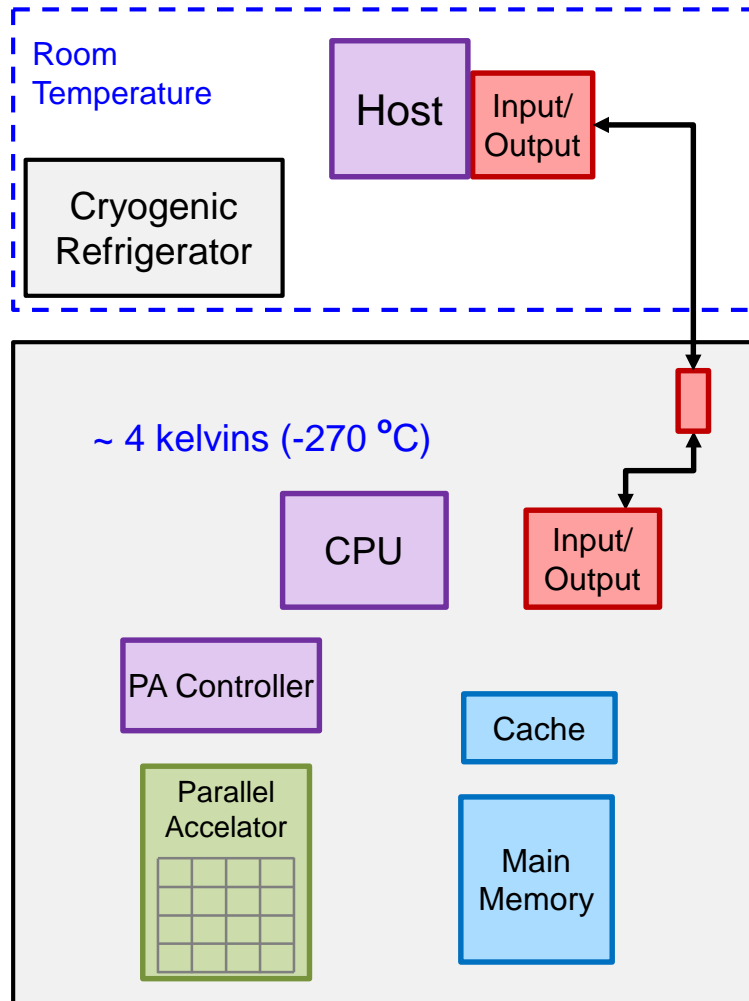
* #1 in Top500, 2012-11 (17.6 PFLOP/s)

- Develop technologies for a computer based on superconducting logic with cryogenic memory, and
- Integrate a prototype that can answer these questions:

- 1) Can we build a superconducting computer capable of solving important problems?
- 2) Does it provide a sufficient advantage over conventional computing that we want to build it?

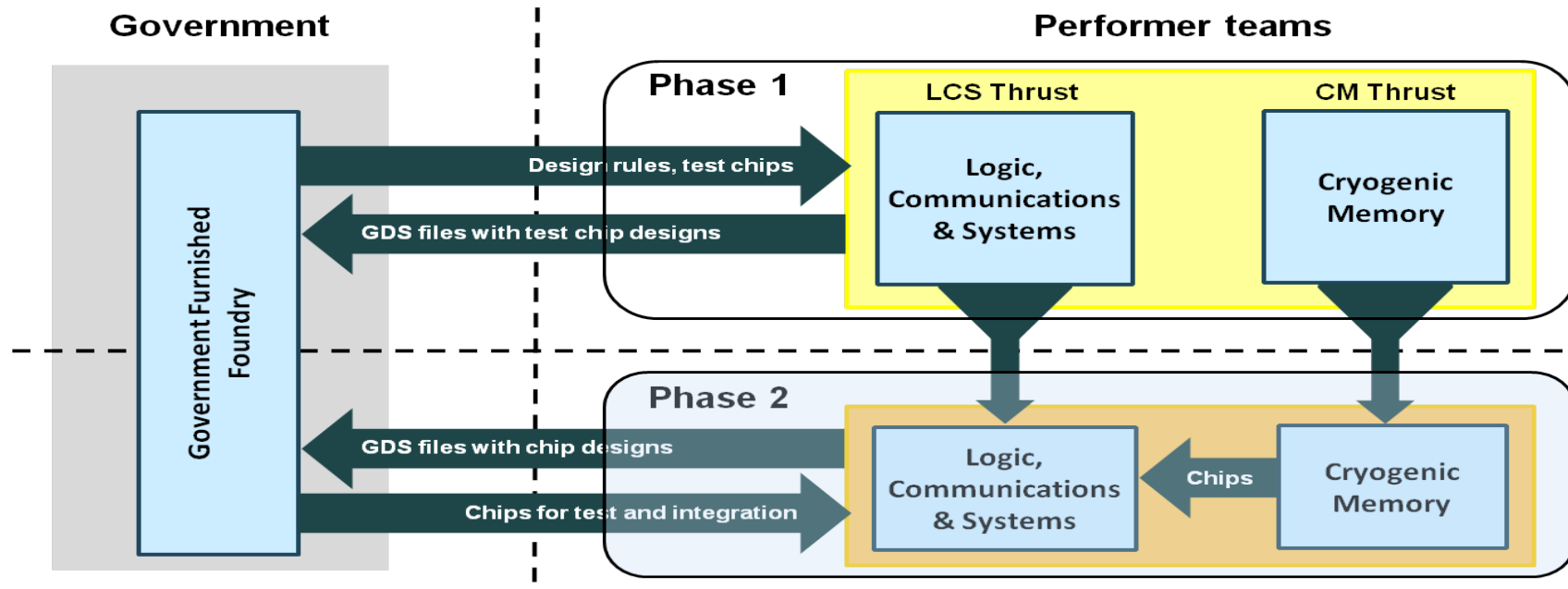
- **Memory:** energy-efficient, fast, dense, useful capacity, compatible with superconducting single flux quantum (SFQ) logic for direct integration
 - C3 ideas include MRAM, spin Hall effect, JM RAM, nMEM
 - Requires interface circuits of significant complexity in SFQ technology
 - Requires understanding new physics with interplay of spintronics and superconductivity
- **Logic complexity:** designing superconducting integrated circuits with far more elements on a single chip than previously achieved
 - In SFQ computing, the devices are Josephson junctions and the logic elements are picosecond wide pulses; these present new design challenges.
 - Electronic design automation tools are either missing or not scalable to very large scale integration

- **Advanced fabrication process:** multilayer, sub-micrometer feature size with specialty layers (high kinetic inductance, milliohm resistance ...)
 - Variance of key fabrication parameters (J_c , inductance) must be improved
 - Must develop detailed simulation module that includes process variations
 - Close coupling between circuit design-test and process design rules is key
 - Need to develop close coupling between foundry and failure analysis team
- **System:** demonstrate a superconducting computer with multiple processors and memory in MCM packaging; beyond C3 challenges include:
 - scalable system design
 - wafer-scale stacking with superconducting through silicon vias
 - high data-rate interconnect between 4 K and room temperature

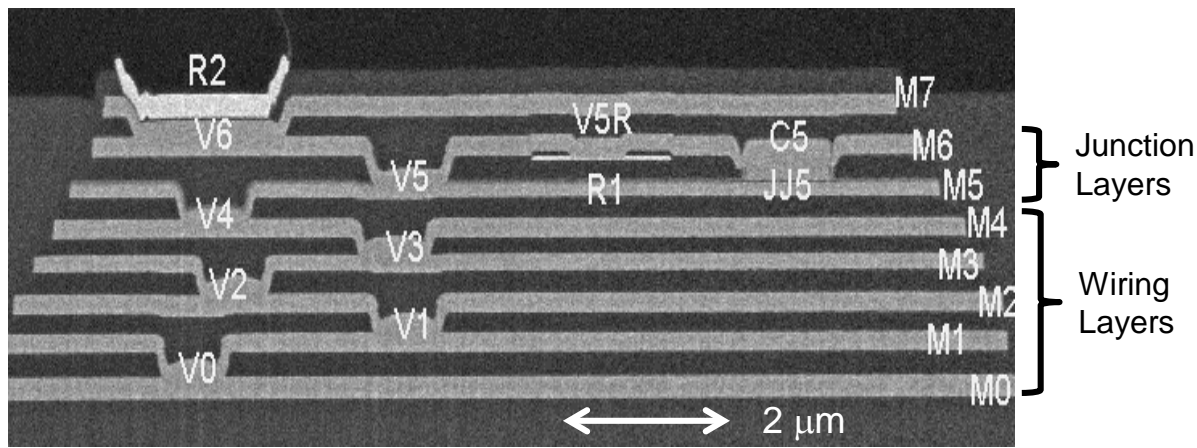


| Metric | Goal |
|--------------------------------------|-----------|
| Clock rate for superconducting logic | 10 GHz |
| Throughput (bit-op/s) | 10^{13} |
| Efficiency @ 4 K (bit-op/J) | 10^{15} |
| CPU count | 1 |
| Word size (bit) | 64 |
| Parallel Accelerator count | 2 |
| Main Memory (B) | 2^{28} |
| Input/Output (bit/s) | 10^9 |

- Two thrusts:
 - Logic, communications and systems (**LCS**)
 - Cryogenic memory (**CM**)
- Two phases:
 - Phase 1, performers develop technology for subsystems
 - Phase 2, performers scale up and integrate technology into a working prototype



- No commercial foundry exists that can fabricate circuits at the required level of complexity.
 - MIT Lincoln Laboratory (LL) has a niobium superconductor circuit foundry that IARPA is upgrading to meet the aggressive program goals.
 - With 200 mm wafers and 8+ planarized niobium layers, **the MIT LL superconducting foundry is now the most advanced in the world – and continues to advance.**
 - LL will transfer the technology elsewhere as directed.
- ✓ Test chips with up to **810,000** JJs all working have been successfully demonstrated in the 8-Nb-layer process.



8 niobium layer cross-section





SFQ Technology Roadmap for IARPA C3



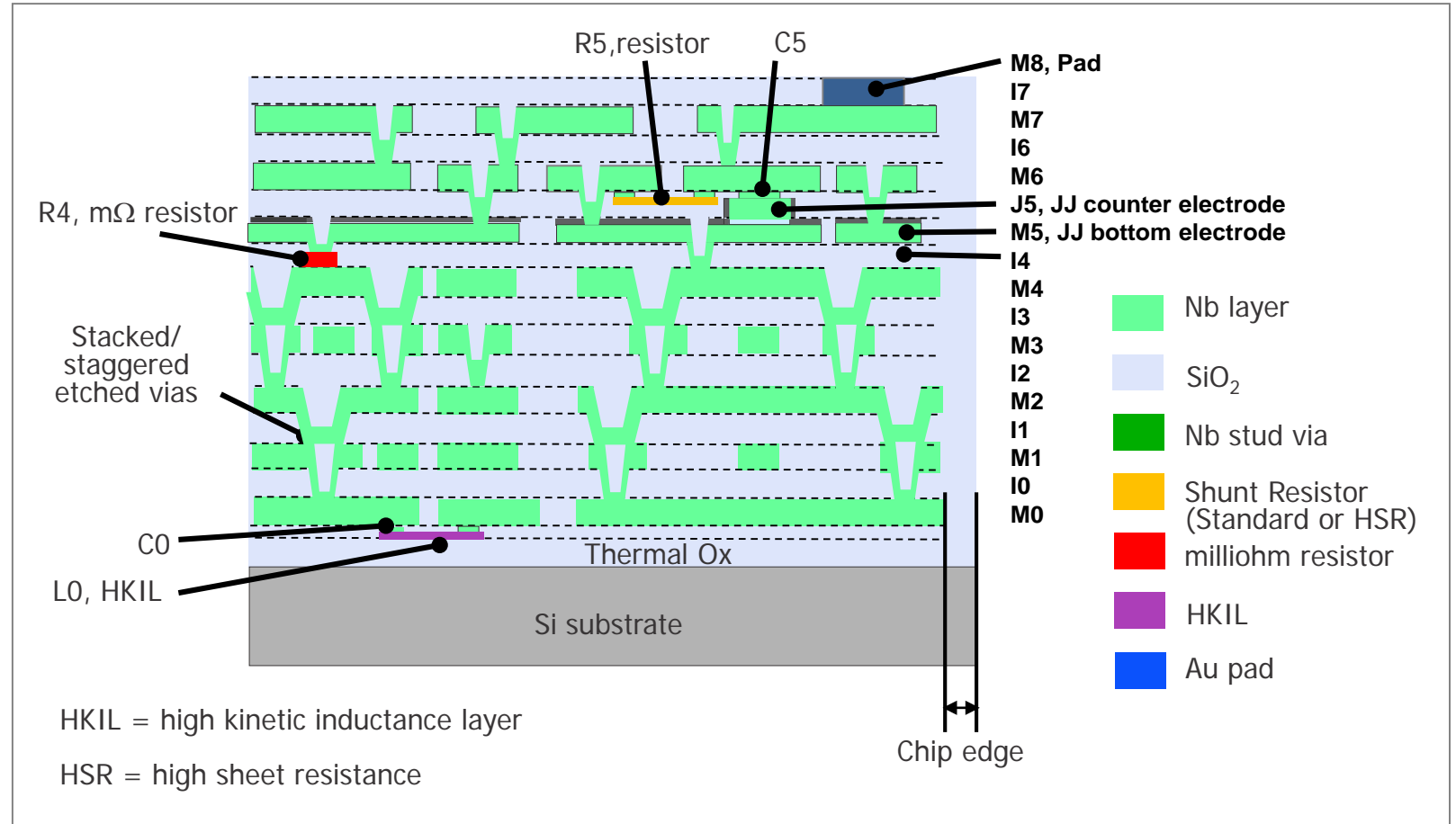
| Fabrication Process Attribute | | Units | Process Node | | | | | |
|-------------------------------|-----------------|-------------------|-------------------|---------------------|---------------------|------------------|---------------------|---------------|
| | | | SFQ3ee | SFQ4ee | SFQ5ee | SFQ6ee | SFQ5hs | SFQ7ee |
| Critical current density | | MA/m ² | 100 | 100 | 100 | 100 | 200 | 100 |
| JJ diameter (surround) | | nm | 700 (500) | 700 (500) | 700 (500) | 700 (300) | 700 (500) | 500 (200) |
| Nb metal layers | | - | 4 | 8 | 8 | 9 | 8 | 10 |
| Line width (space) | Critical layers | nm | 500 (1000) | 500 (700) | 350 (500) | 350 (400) | 350 (500) | 250 (250) |
| | Other layers | nm | | | 500 (700) | 500 (700) | 500 (700) | 350 (500) |
| Metal thickness | | nm | 200 | 200 | 200 | 200 | 200 | 200 |
| Dielectric thickness | | nm | 200 | 200 | 200 | 200 | 200 | 200 |
| Resistor width (space) | | nm | 1000 (2000) | 500 (700) | 500 (500) | 500 (500) | 500 (700) | 350 (350) |
| Shunt resistor value | | Ω/sq | 2 | 2 | 2 or 6 | 2 or 6 | 2 or 6 | 2 or 6 |
| mΩ resistor | | mΩ | - | - | 3 - 10 | 3 - 10 | 3 - 10 | 3 - 10 |
| High kinetic inductance layer | | pH/sq | - | - | 8 | 8 | 8 | 8 |
| Via diameter (surround) | | nm | 700 (500) | 700 (500) | 600 (300) | 500 (250) | 500 (350) | 350 (250) |
| Via type, stacking | | - | Etched, Staggered | Etched, Stacked \2/ | Etched, Stacked \2/ | Stud Stacked \2/ | Etched, Stacked \2/ | Stud, Stacked |
| Early access availability | | - | 2013 | 2014 | 2015 | 2016 | 2017 | 2018 |

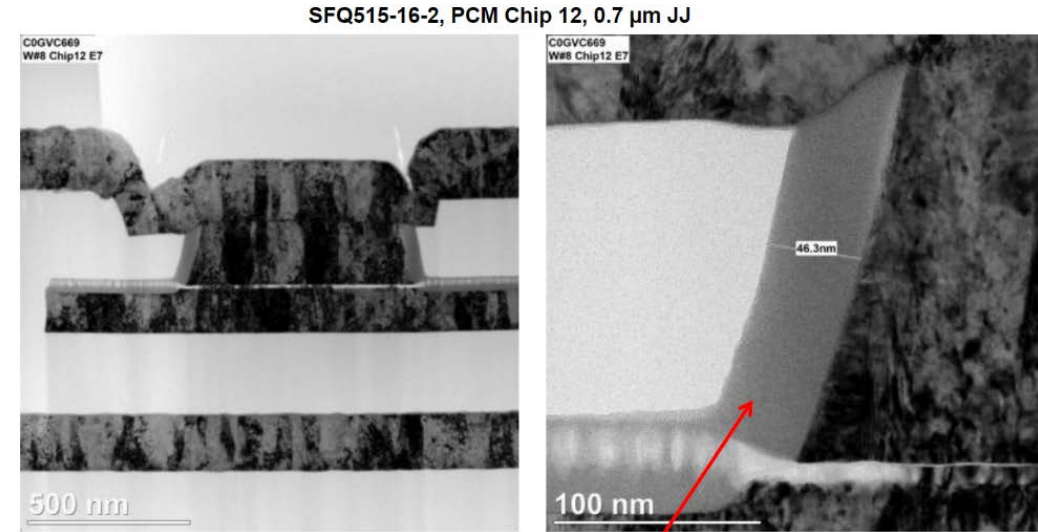
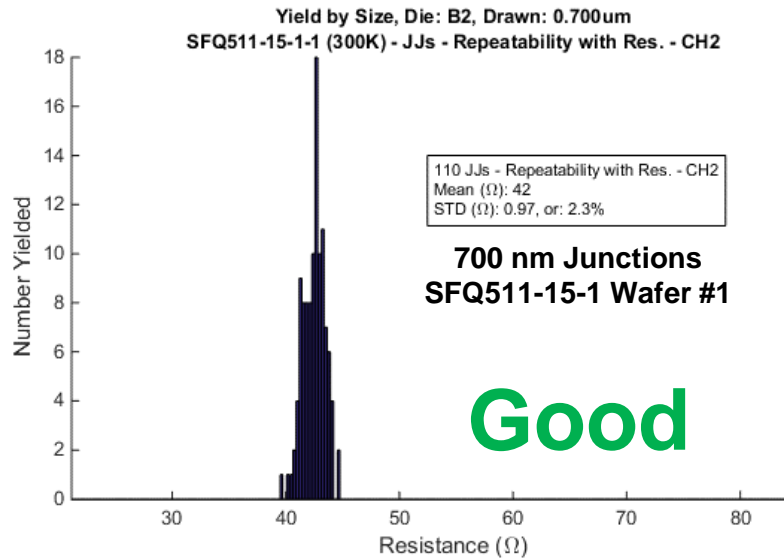
October 2017 update

Changes from the previous process

Stopped here!

- 8 Nb layers
- 700 nm (min.) Josephson junctions
- JC target: 100 $\mu\text{A}/\text{mm}^2$
- Wiring (min.): 350 nm width, 500 nm spacing
- Options:
 - High kinetic inductance (HKI) layer
 - High sheet resistance (HSR) layer

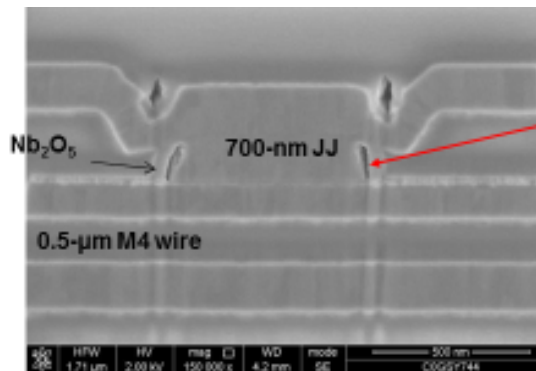
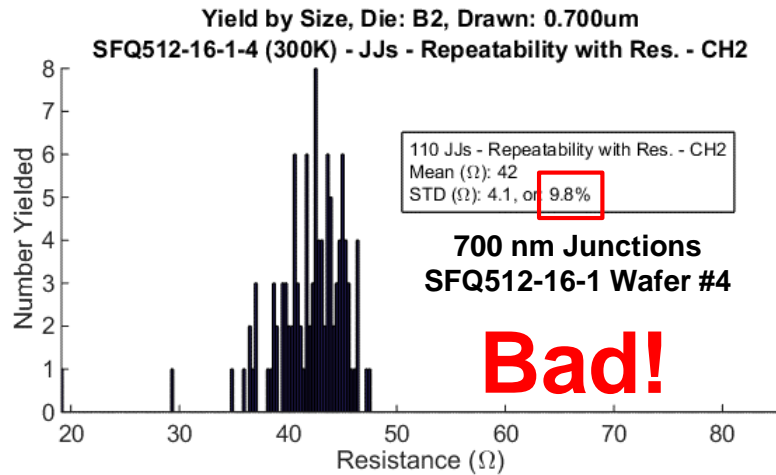




Wafer #8 Loc E7

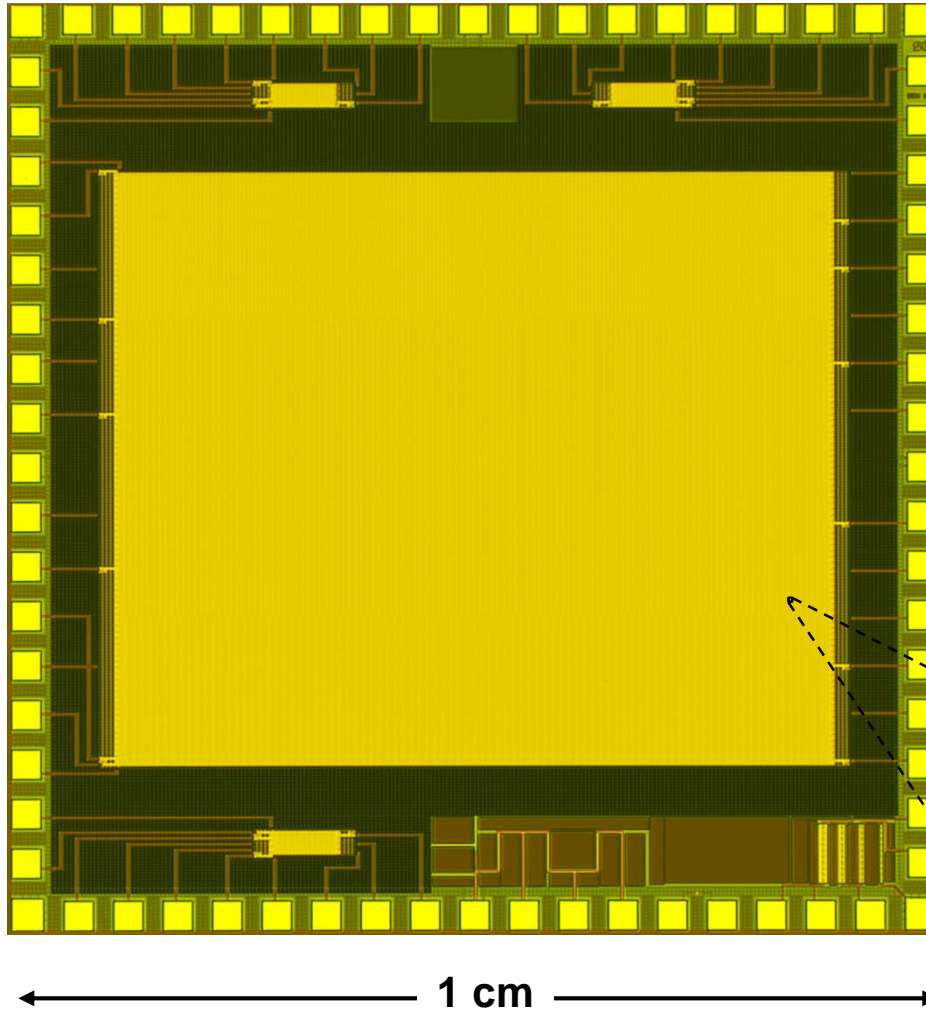
Anodization layer

FIB/TEM images from EAG
29 Dec 2016

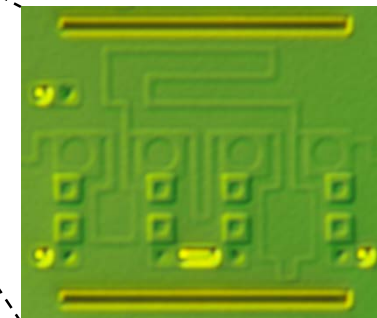


Delamination of anodized Nb_2O_5 , possibly due to topography-related stress during CMP

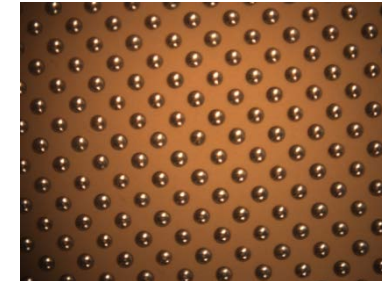
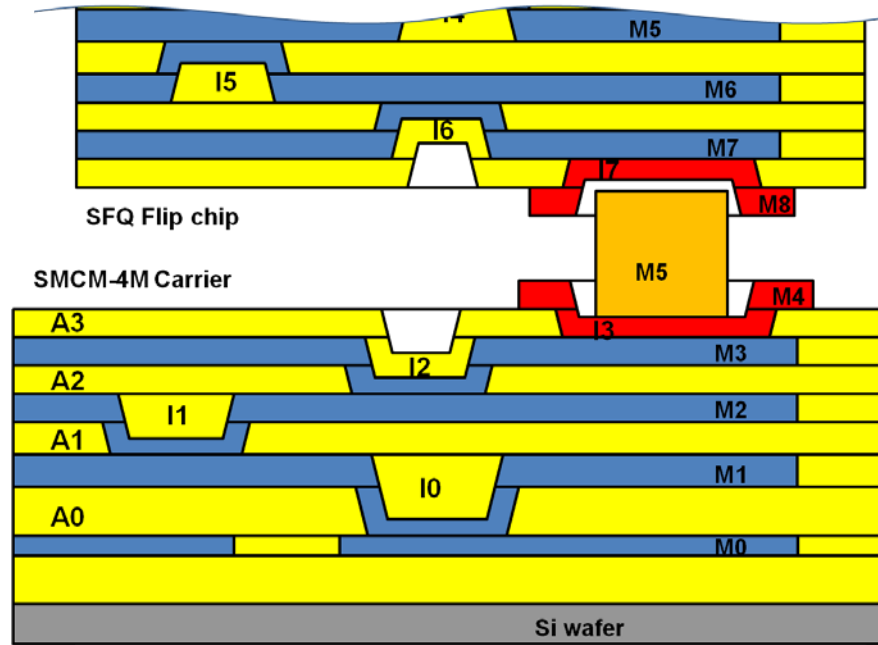
- FIB cross sections of the damaged junctions on M4 and on M3+M4 wires indicate Nb_2O_5 delamination/cracking in 100% of the cross-sectioned JJs
- Possible damage mechanism
 - delamination (cracking) of the anodization layer protecting the JJ interior
 - reaction of the exposed AlO_x tunnel barrier with the environment



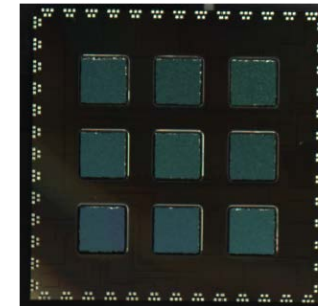
- MIT LL process monitor circuit
- 202,280-bit shift register
- 810,000+ JJs on 1 cm² chip
- Cell size: 20 μm x 15 μm
- JJ density: $1.33 \cdot 10^6$ JJ/cm²
- Status: fabricated, operational with margins
- **Integration scale:** close to Intel's 1993 Pentium: 0.8 μm process, 3.1 M transistors on a 294 mm² chip



← 1 bit cell



15- μm indium bumps on 35 μm pitch



9-chip (SFQ) on S-MCM assembly

MIT Lincoln Laboratory

- Flip-chip attachment of SFQ chips to S-MCM carriers
- Indium bumps: 8-15 μm diameter on 35 μm pitch
- Up to $7 \cdot 10^4$ bumps per chip in flip-chip MCMs demonstrated
- 32 mm x 32 mm MCM size (up to 5 cm by 5 cm possible), i-line photolithography

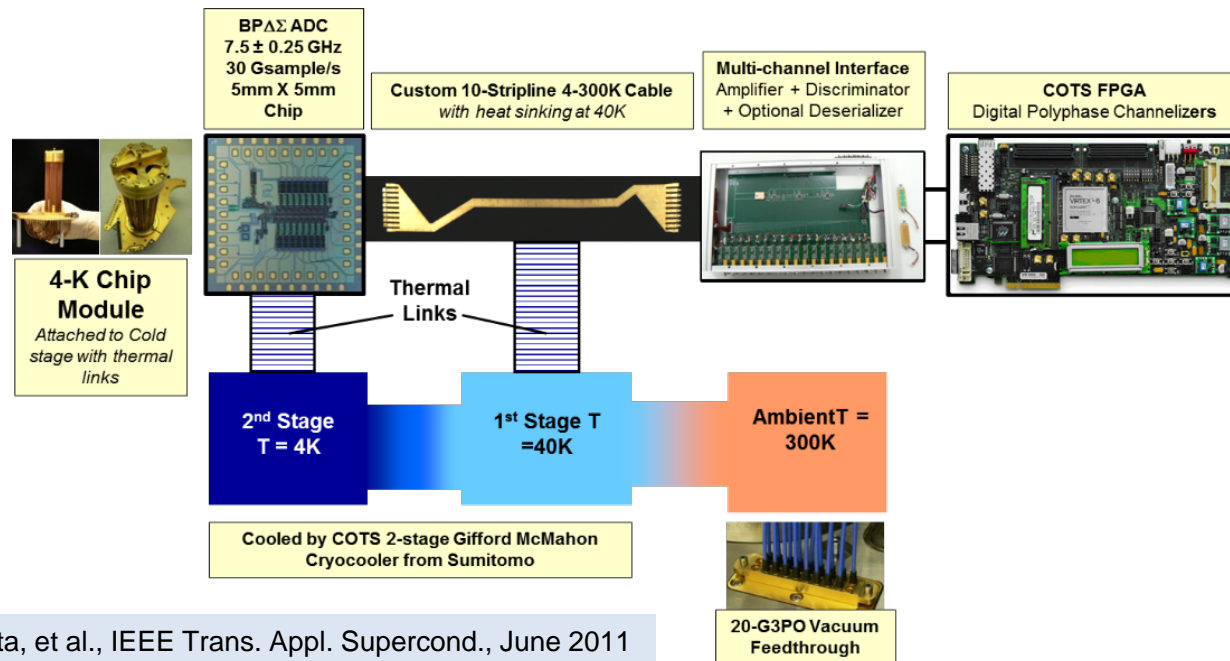


Related Work

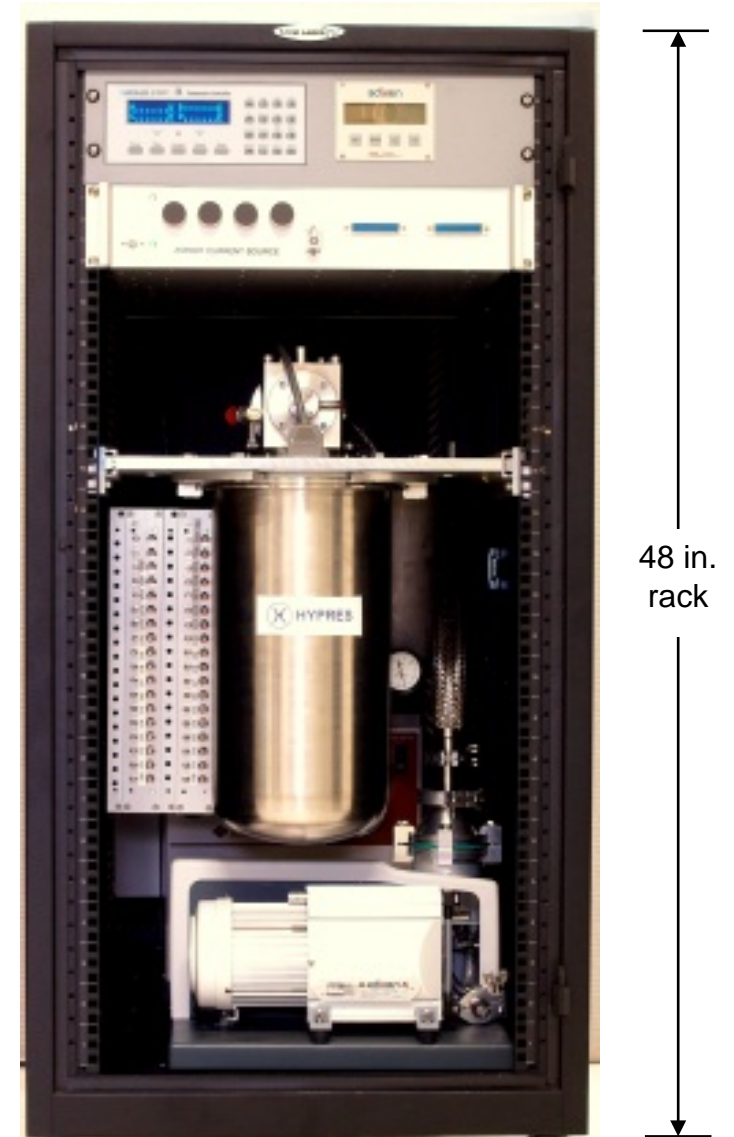


Digital-RF receiver (Hypres)

- Commercial product with applications in:
 - Software-defined radio, satellite communications
- Directly digitizes RF (no analog down-conversion)
 - Ultra-wide bandwidth, multi-band, multi-carrier
- Hybrid temperature heterogeneous technology
 - Different technologies between ambient and 4 K
 - Closed-cycle cryogenic refrigerator



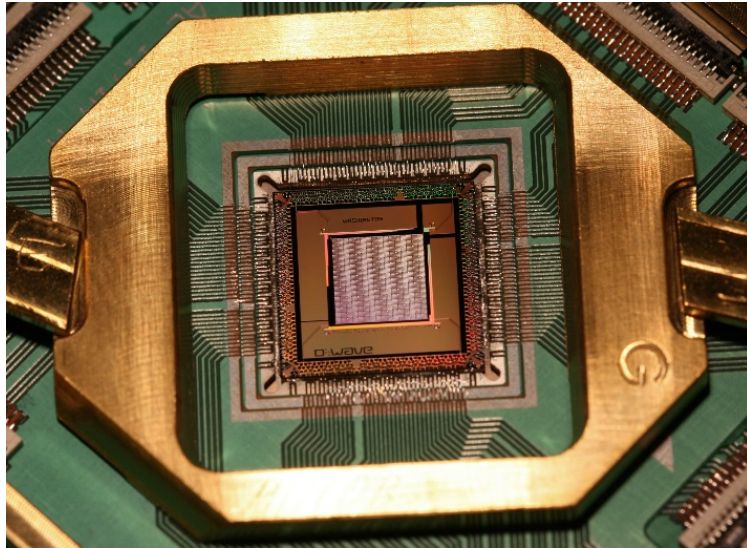
Gupta, et al., IEEE Trans. Appl. Supercond., June 2011





Quantum annealing (D-Wave Systems)

- D-Wave® TwoX™ (2015 August 20), a commercial superconducting quantum annealing processor
- 128,000 Josephson junctions
- 1000 qubit array
- 15-20 mK operating temperature



"Washington" chip



D-Wave® TwoX™ quantum annealing processor



Can China build a US\$145 million superconducting computer that will change the world?

Chinese scientists are embarking on a one-billion yuan, high-risk, high-reward plan to build low-energy top-performance computing systems

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UPDATED : Monday, 27 August, 2018, 12:44pm

COMMENTS: 57

<https://www.scmp.com/news/china/society/article/2161390/can-china-build-us145-million-superconducting-computer-will>

- Superconducting digital circuits and superconducting computers
- 100 mm foundry (currently)







AQFP logic is achieving extremely low energy computation

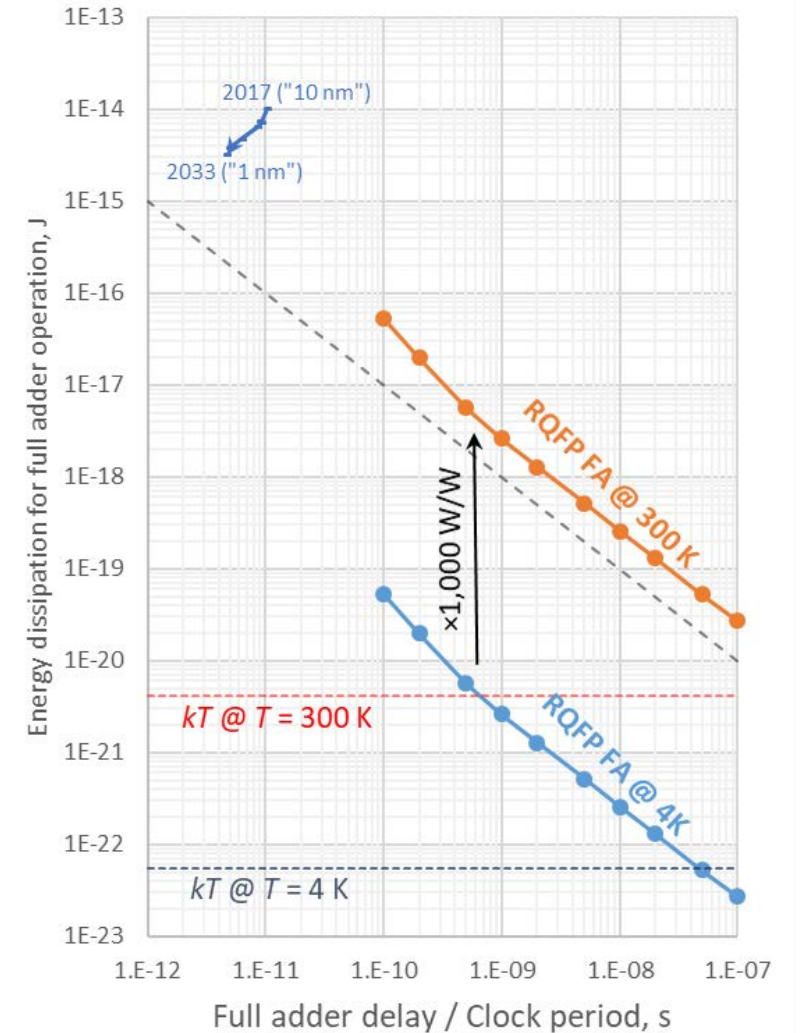
ics Letters

An adiabatic superconductor 8-bit adder with $24k_B T$ energy dissipation per junction

Cite as: Appl. Phys. Lett. **114**, 042602 (2019); <https://doi.org/10.1063/1.5080753>
Submitted: 12 November 2018 . Accepted: 14 January 2019 . Published Online: 29 January 2019

Naoki Takeuchi , Taiki Yamae , Christopher L. Ayala , Hideo Suzuki, and Nobuyuki Yoshikawa 

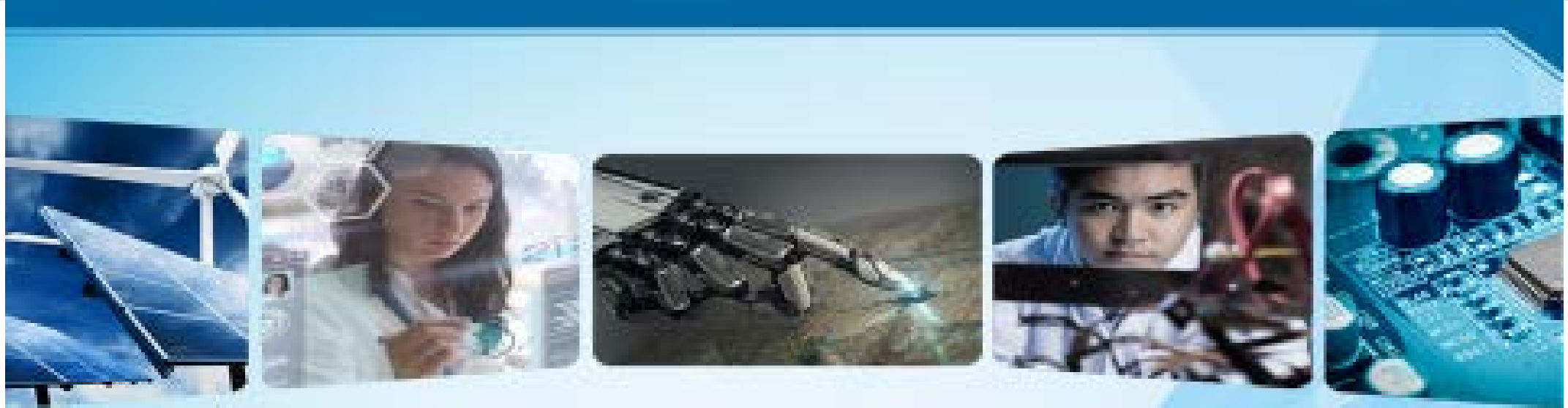
Energy & delay for full adder cell



Plot by M. Frank, Sandia National Laboratories



International Roadmap for Devices and Systems (IRDS)



IRDS Spring Meeting IFT Cryogenic Electronics and Quantum Information Processing Read-out

*IEEE International Nanodevices and Computing Conference (INC)
Grenoble France*

4 April, 2019



2. Superconductor Electronics (SCE)

2.1. Introduction

2.2. Applications and Market Drivers for SCE

- 2.2.1. Cloud (Digital Computing)
- 2.2.2. Measurement & Calibration Systems
- 2.2.3. Communications

2.3. Present Status for SCE

- 2.3.1. Logic
- 2.3.2. Memory
- 2.3.3. Other Circuit Elements for SCE
- 2.3.4. Architecture
- 2.3.5. Fabrication for SCE
- 2.3.6. Electronic Design Automation (EDA) for SCE
- 2.3.7. Packaging and Testing for SCE
- 2.3.9. Interconnects for SCE
- 2.3.10. Refrigeration

2.4. Benchmarking and Metrics for SCE

- 2.4.1. Device and Circuit Benchmarking
- 2.4.2. System and Application Benchmarking

2.5. Active Research Questions for SCE

2.6. Roadmap for SCE

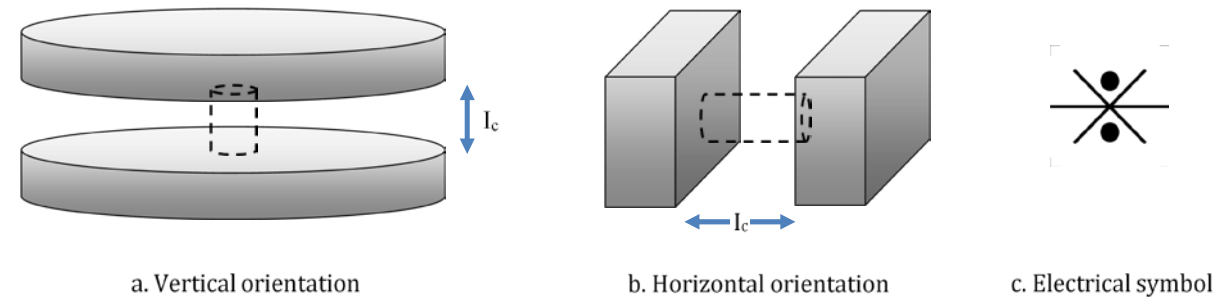
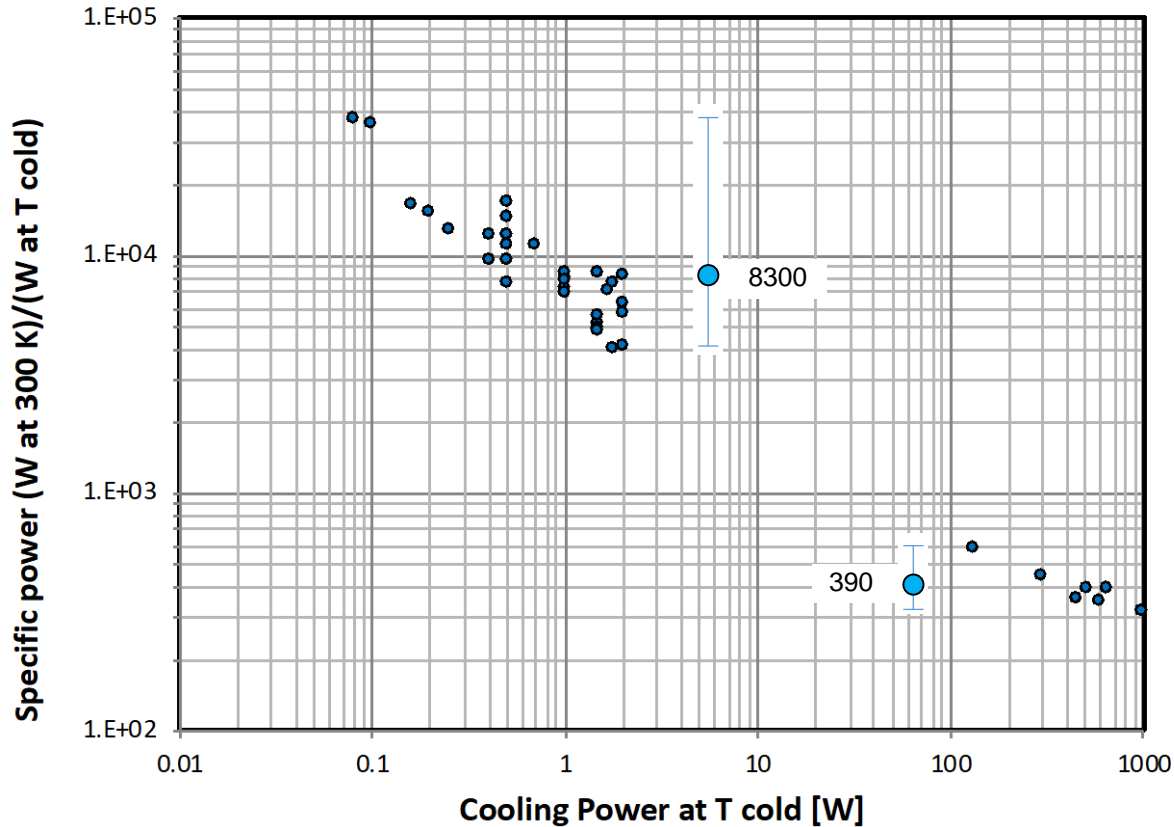


Figure CEQIP-1. Josephson Junction Device Structures

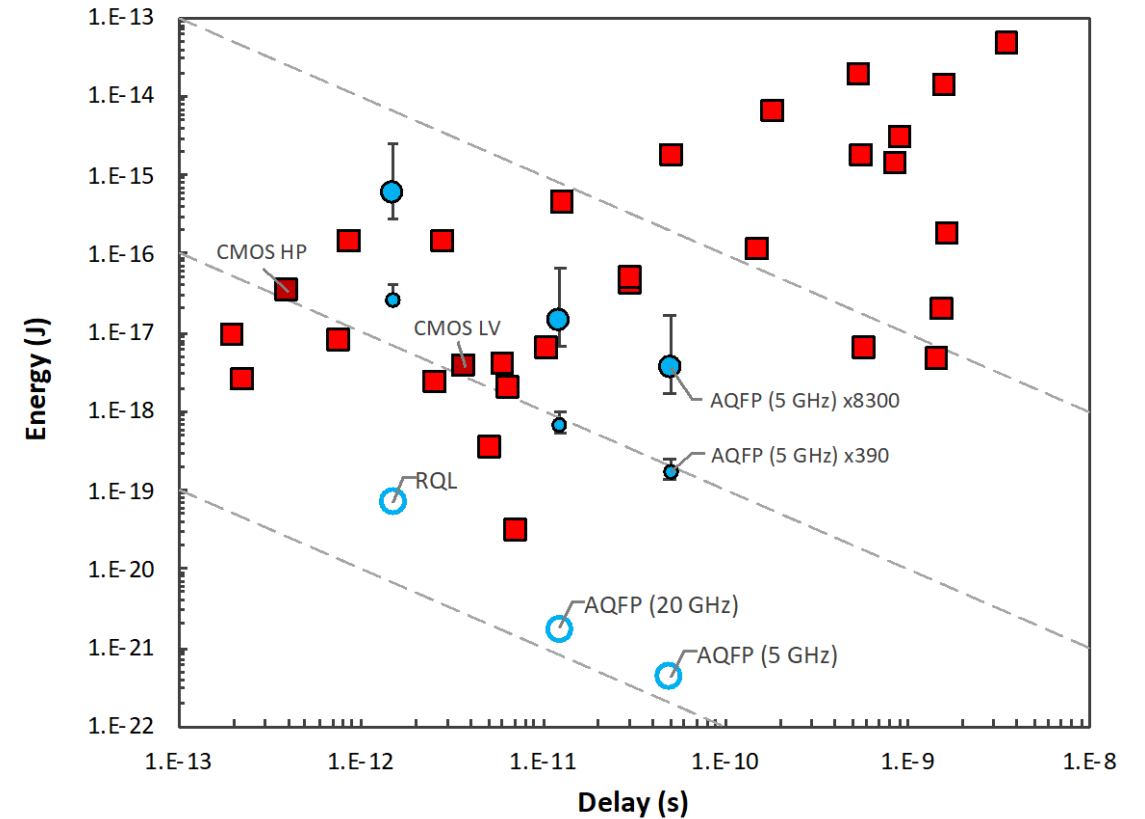


Benchmarking and Metrics for SCE (IRDS CEQIP 2018)

Methodology established for comparison with other technologies



Cryogenic Refrigeration Systems for T ~ 4 K



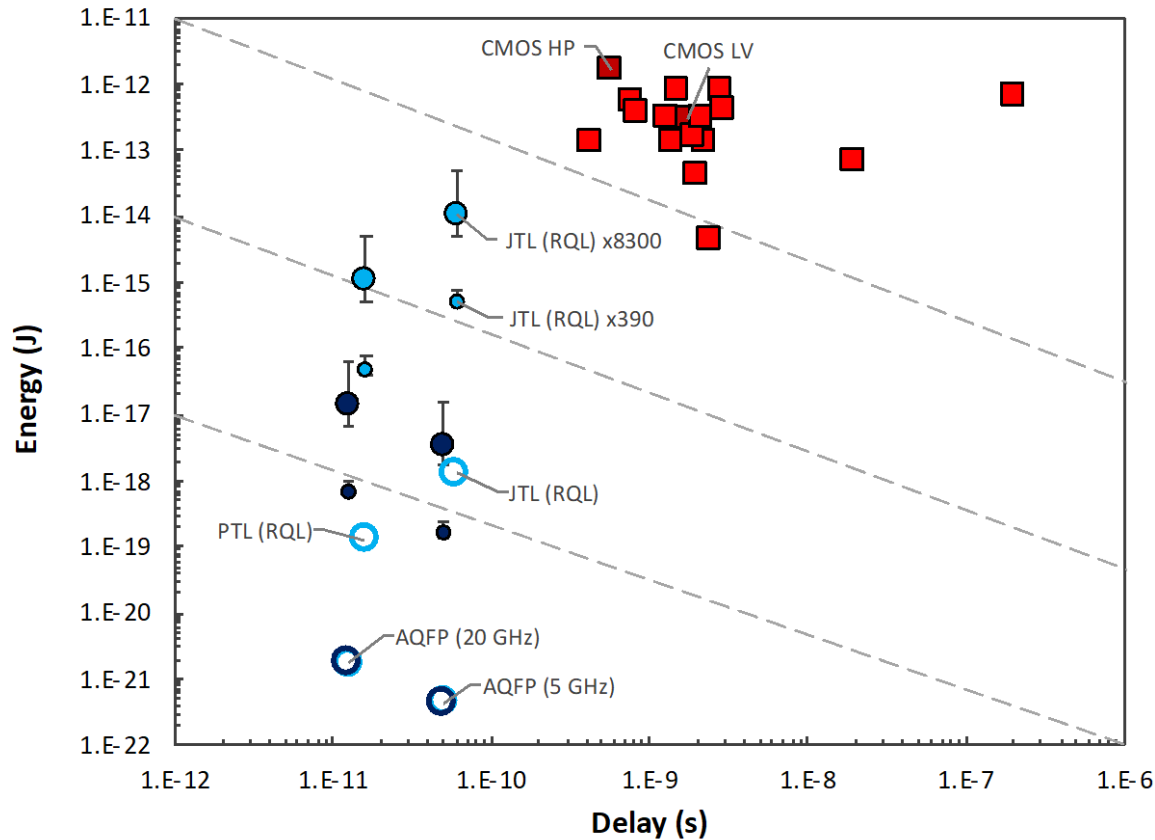
Energy versus delay for intrinsic elements

Note: Superconductor devices (AQFP, RQL) have open circles for operation at ~4 K and solid circles with whiskers showing ranges including refrigeration power from Table CEQIP-7. The upper solid circles with ranges are for small-scale refrigerators (cryocoolers) with cooling powers less than 10 W. All other devices are from [359]. Dashed lines show constant energy-delay products.

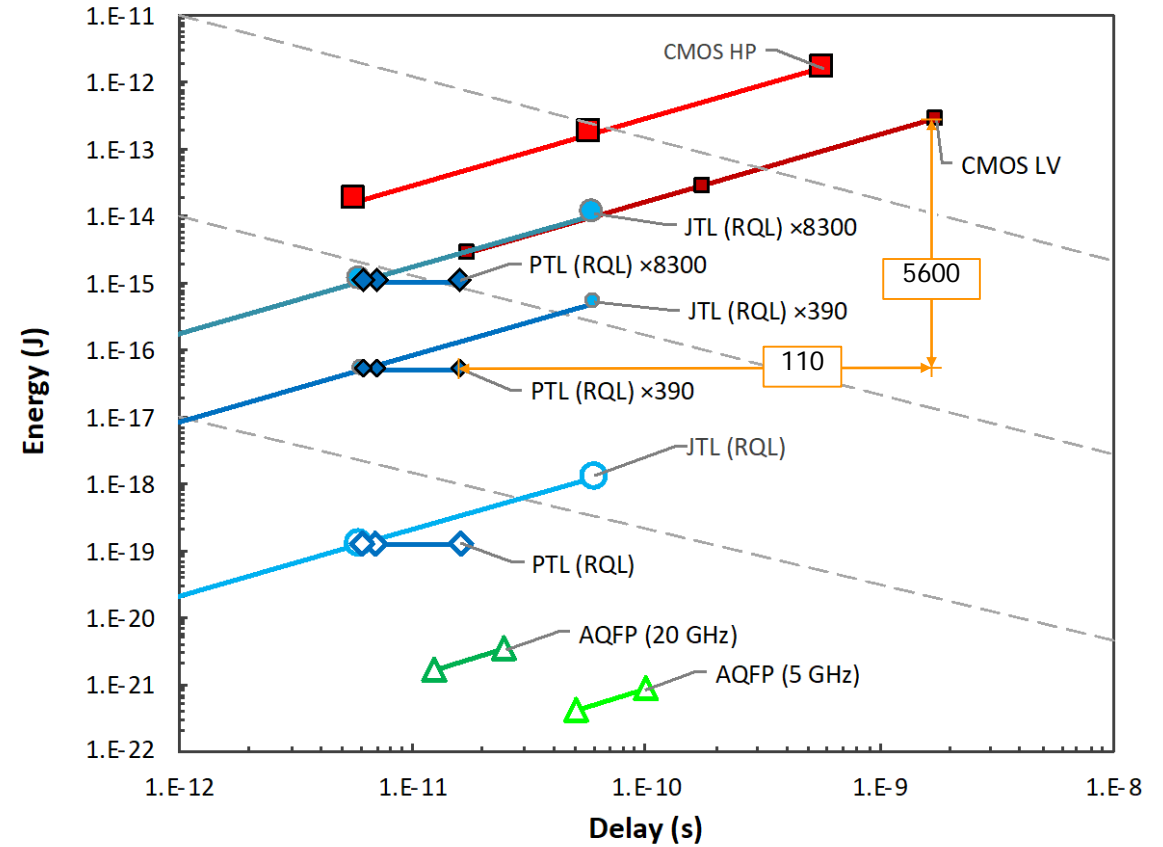


Benchmarking and Metrics for SCE (IRDS CEQIP 2018)

Methodology established for comparison with other technologies



Energy versus Delay for Interconnects of 1 mm Length



Energy versus delay for 0.01 to 1 mm Length

Note: Superconductor devices (AQFP, RQL) have open circles for operation at ~4 K and solid circles with whiskers showing ranges including refrigeration power from Table CEQIP-7. The upper solid circles with ranges are for small-scale refrigerators (cryocoolers) with cooling powers less than 10 W. All other devices are from [359]. Dashed lines show constant energy-delay products.

- **Models** for devices and circuits
 - Variety of superconductor technologies (e.g., RSFQ, AQFP)
 - Core metrics: circuit area, delay, and energy
 - Scaling models
- **Models** for applications
 - Logic, Memory, Interconnects
- **Roadmap**
- Connect to SA, AB, ORTC, ORSC

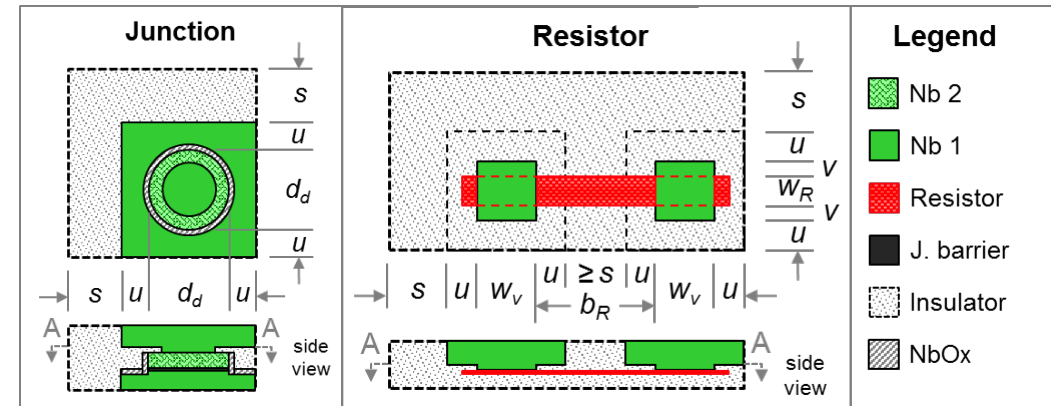
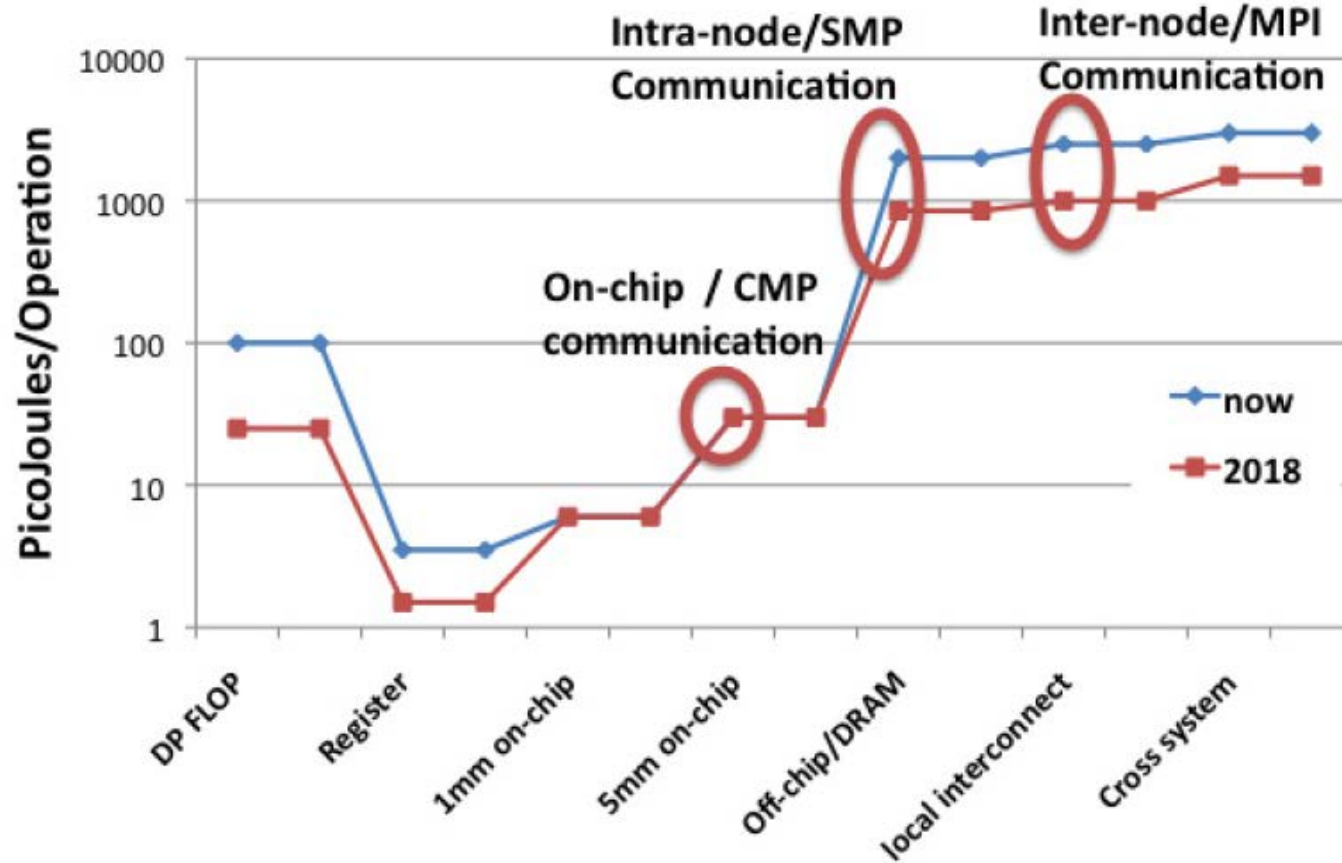


Table 2. IC technology roadmap.

| | 1998 | 2001 | 2004 | 2007 | SIA 1992 |
|---|------------|-------|-------|--------|-------------|
| Minimum feature size (μm) | 1.5 | 0.8 | 0.50 | 0.25 | 0.50 |
| Junction size (μm) | 2.5 | 0.8 | 0.80 | 0.80 | — |
| Critical current (A cm^{-2}) | 2k | 20k | 20k | 20k | — |
| Gates per chip (logic) | 5k | 120k | 600k | 2M | 300k |
| Bits per chip (SRAM) | 16k | 400k | 2M | 6M | 4M |
| Chip size (mm^2) | 100 | 400 | 400 | 400 | 250 |
| Wafer diameter (mm) | 100 | 150 | 150 | 150 | 200 |
| Defects per cm^2 | < 2 | < 0.2 | < 0.1 | < 0.05 | < 0.1 |
| Number of interconnect levels | 3 | 4–5 | 5–6 | 6 | 3 |
| Number of resistor layers | 2 | 2 | 2 | 2 | — |
| Planarization | No | Yes | Yes | Yes | Yes |
| Vertical resistors | No | No | Yes | Yes | — |
| I/O count | 128 | 2k | 2–5k | 2–5k | 500 |
| Wafer starts per month | 12 | 200 | 1k | 1k | > 20k |
| | SCE | | | | CMOS |

Abelson et al. (1999) "Manufacturability ..." doi: 10.1088/0953-2048/12/11/363



- Needed: comparison with SCE!

Fig. 2. Energy cost of data movement relative to the cost of a flop for current and 2018 systems

Plot: Shalf, Dosanjh, Morrison, "Exascale Computing Technology Challenges," 2011, doi:10.1007/978-3-642-19328-6_1
 Slide: IRDS_Spring2019_Read-out_CE&QIP



DIFFICULT CHALLENGES for SCE (IRDS CEQIP 2018)

Technology Road Blocks...Highlight gaps and showstoppers, possible disconnects within the roadmap

- Near term
 - EDA tools for superconductor electronics
 - EDA tools for CMOS are not adequate for SCE. Inductance is critical in superconducting circuits and connecting wires must have inductance values within a specified range. Circuit simulators and timing analysis must be modified for pulse-based logic.
 - PDKs for fabrication processes
 - Complete process design kits (PDKs) are needed for fabrication processes for superconductor electronics.
 - Yield improvement of circuits with > 1 M Josephson junctions (switching devices)
 - Variation in device parameters reduces the operating margins of circuits. Needed is better process control, better device designs, or circuit designs that tolerate or compensate for device variability.
- Long term
 - Temperature limits compatible with CMOS fabrication processes
 - Nb/Al-AIO_x/Nb Josephson junctions are sensitive to temperature. Fabrication processing temperatures are currently limited to less than 200 °C, which requires different processes than those used in CMOS technology, which has a limit of 400 °C.
 - Optical input/output (I/O)
 - Communication with room-temperature systems and networks will require a high-data-rate I/O, but interconnection cannot introduce significant heat into a low-temperature environment. Optical fiber digital links would be ideal, but efficient SFQ-to-optical converters must be developed.
 - Magnetic materials fabrication process integration
 - Magnetic materials are desired to make both memory and passive devices. Integrating magnetic materials into foundry processes will be difficult.



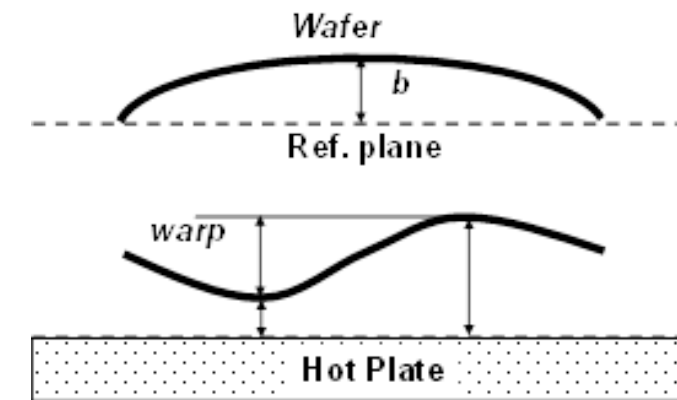
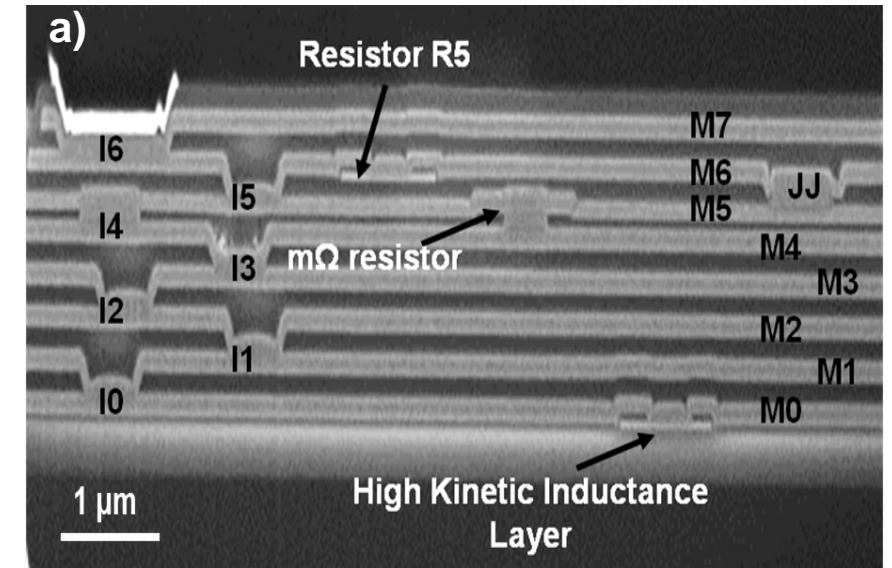
Challenges Remaining for Superconductor Electronics (SCE)



Challenges

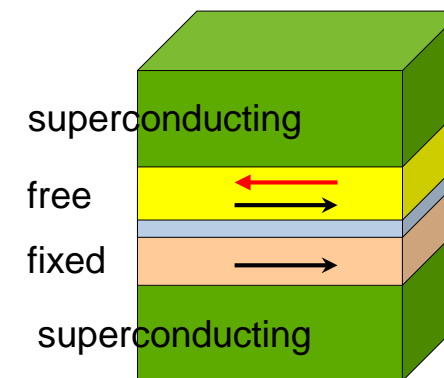
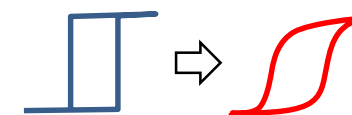
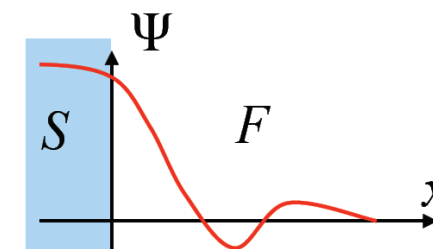
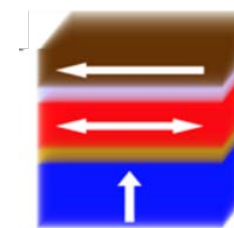
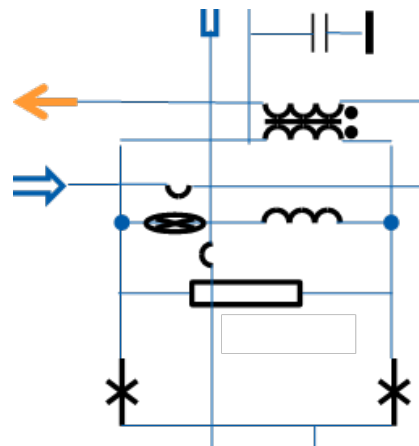
- Fabrication
 - Memory
 - Magnetic memory device physics and fabrication
 - Cell size
 - Superconducting circuit physics
 - Coupled current and inductance
 - Low gain from JJs
 - Electronic design automation (EDA) tools
 - Input/Output
 - Optical needed
 - High-speed, low heat leak
 - Circuit complexity, density
 - Cryogenic and (non-) magnetic environment
 - Materials and packaging
 - Refrigeration
- } Subject of other talks
- } Future

- JJs are near the top of layer stack in SFQ5ee and SFQ6ee processes
- 6 to 7 patterned metal layers below
- Signal routing challenges with split wiring layers above and below the JJs
- JJ parameter spreads above patterned wires are $\sim 1\%$ larger than for JJs above ground plane
- 6 layers of SiO_2 dielectric with $\sim 1 \mu\text{m}$ total thickness below the JJs
- Residual stress in PECVD $\text{SiO}_2 \sim -200 \text{ MPa}$ (compressive) and higher for HD PECVD
- Residual stress creates wafer bow of $60 \mu\text{m}$ to $70 \mu\text{m}$
- Patterned and planarized metal layers create nonuniform stress because of nonuniform thickness of dielectric
- Wafers warp: $\sim 60 \mu\text{m}$ typical

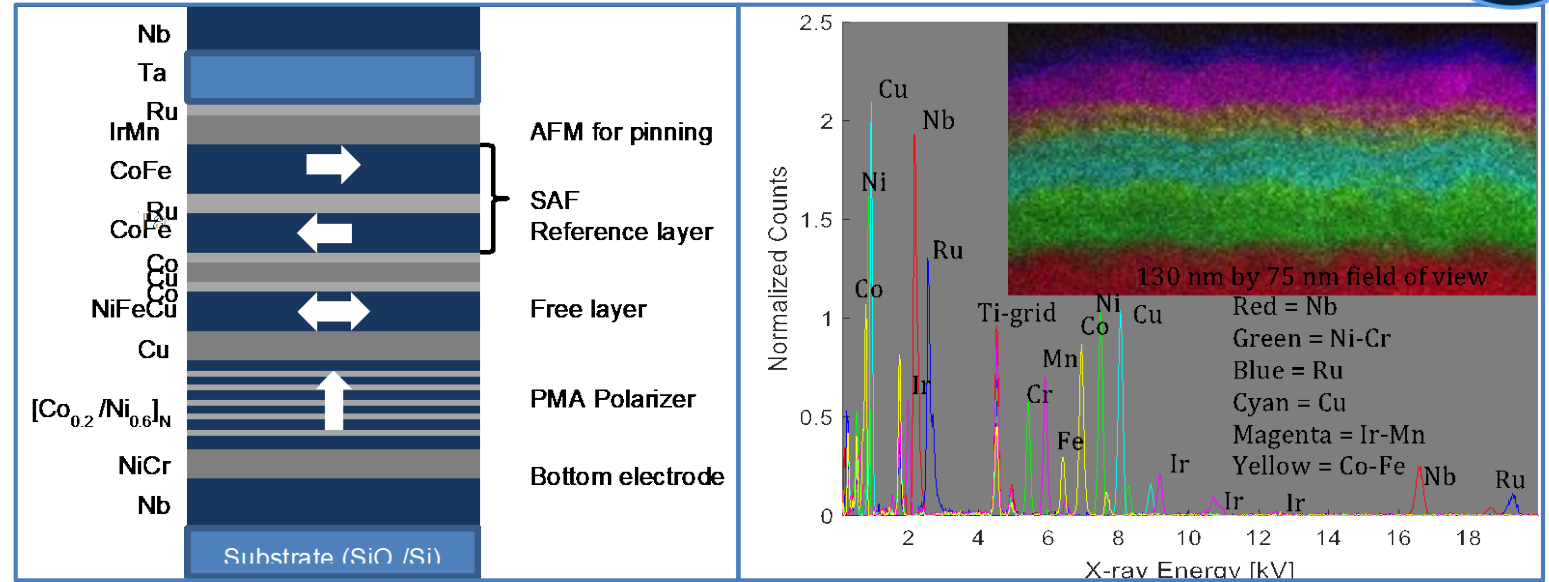


Wafer bow and warp

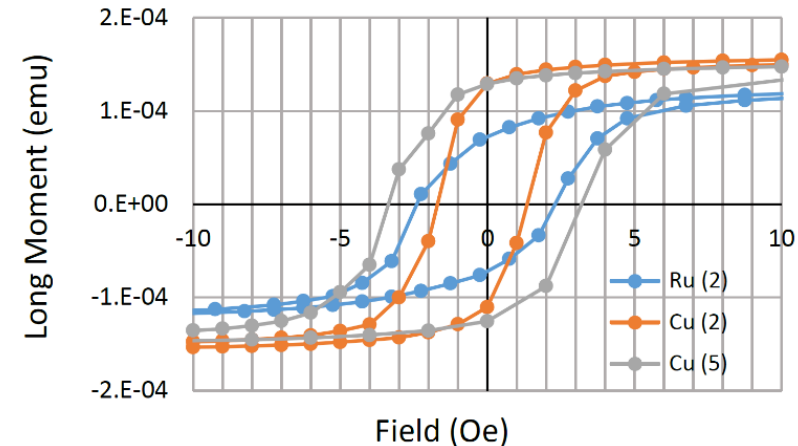
- Variety of device types with no clear winner
 - Magnetic spin valve (SV), spin Hall effect (SHE), spin-transfer torque (STT), ...
 - New materials: NiFeMo, NiFeCu, NiFeNb, Co/Ru/Co, [Co/Ni]_n, ...
 - New physics combining spintronics and superconductivity
- Process control
 - Low energy operation and superconductivity demand thin layers
 - Thickness (~ 1 nm) exponentially affects device parameters
 - Interfacial roughness degrades properties and increases spreads
 - Properties change from room temperature to 4 K
- Memory cell size
 - Multiple devices per cell
 - No equivalent to DRAM yet



- Optimizing magnetic layers
 - Shape, size
 - Thickness
 - Materials
 - Temperature dependence
 - Fabrication
 - Crystalline anisotropy
 - Smoothness
 - Uniformity
 - Hygiene effects
- Decoders
- Drivers
- System requires integration of diverse technologies onto a single substrate

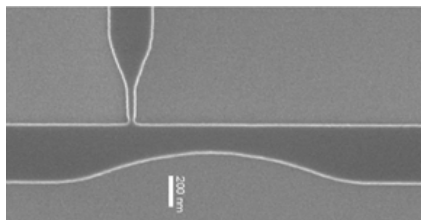


Thin Spacer Comparison

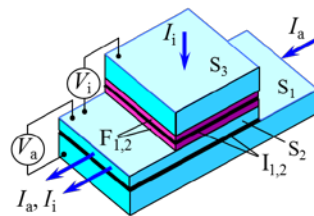


[Nb(25)/Al(2.4)]₃/Nb(20)/Spacer/NiFe(1.5)/Spacer/Nb(5)

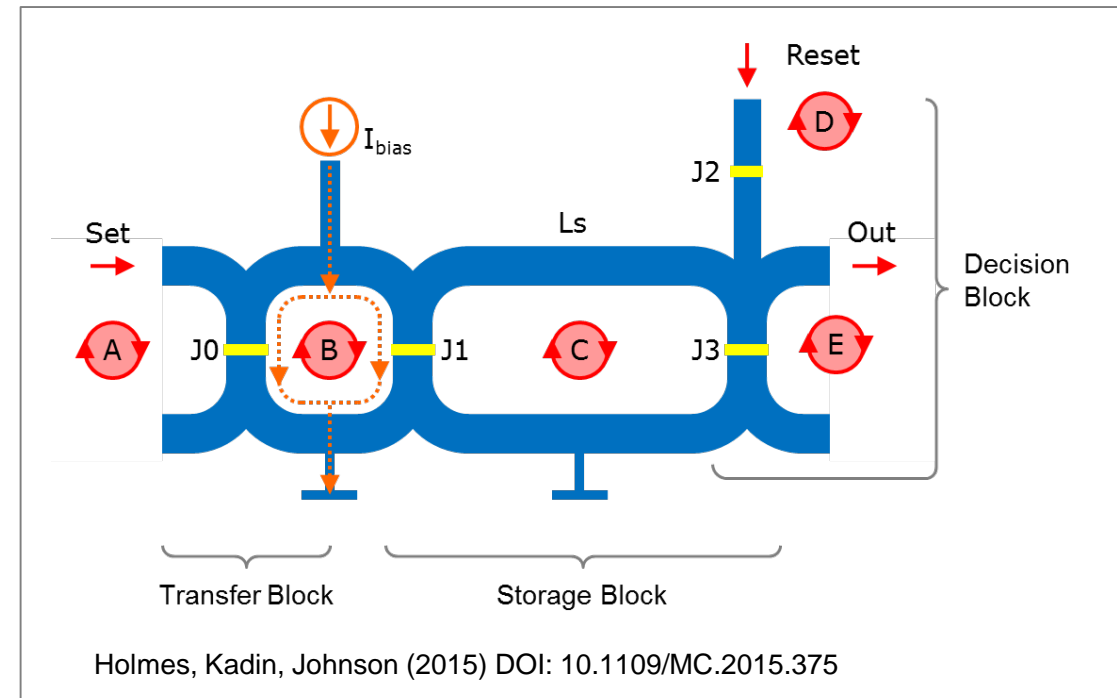
- Inductance (L) and critical current (I_c) are linked for SFQ circuits
 - SFQ: Single Flux Quantum, $\Phi_0 = 2.07 \text{ fWb}$ (mV·ps or mA·pH)
 - Flux: $I \cdot L = \Phi = \alpha \Phi_0 \approx \Phi_0$ **required for circuit operation!**
 - Switching energy: $E_{sw} = I_c \cdot \Phi_0$
 - **Decreasing** I_c (more energy efficient!) requires **increasing** L
- Low gain
 - Fan-out > 1 requires splitters
 - Low gain from Josephson junctions (3 JJs to make a 2:1 splitter)
 - Low isolation across JJs
 - Alternatives are being explored



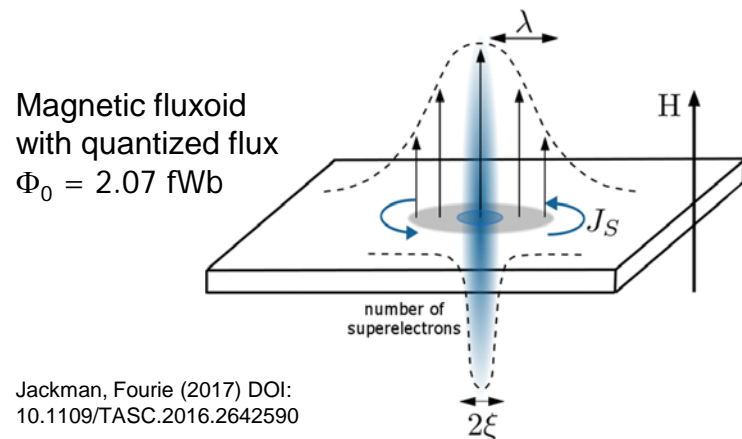
3-terminal nanowire switch



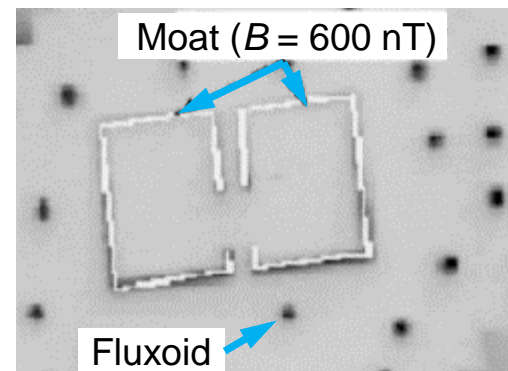
S-F transistor



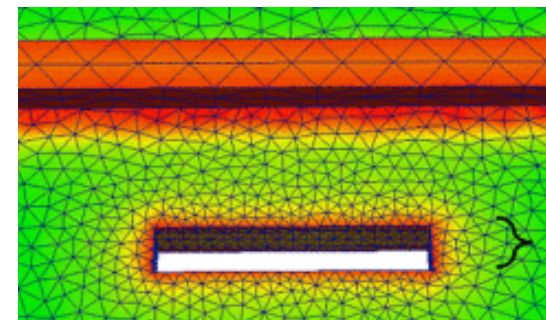
- Currents (I) and inductances (L) are important in superconductor digital logic compare to voltages (V) and capacitances (C) for CMOS
- Fault or failure mechanisms are different for superconductor circuits
 - Cosmic rays, radiation? No problem.
 - Magnetic fields from Earth or electric currents? Can cause faults due to trapped flux.
- Fault characteristics: circuit behavior is not as designed and varies by cooldown
- Magnetic flux in superconductors
 - Excluded at low magnetic flux density (B), but penetrate as quantized fluxoids above a critical value (B_{c1})
 - Mitigation: “moats” (holes in the superconducting ground plane) that trap flux away from sensitive circuits
 - Worst case: circuit must be warmed above superconducting temperature (Nb $T_c \sim 9$ K)



Jackman, Fourie (2017) DOI: 10.1109/TASC.2016.2642590

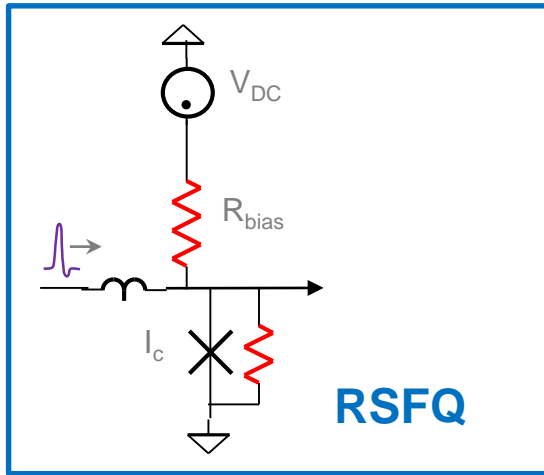


Kirtley, Wilkswow (1999) DOI: 10.1146/annurev.matsci.29.1.117

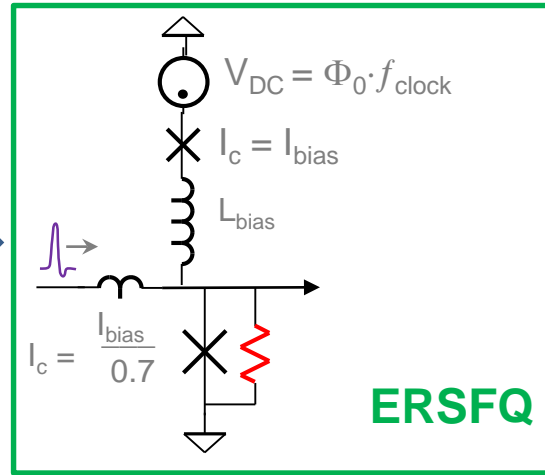


Fluxon trapped in a moat and away from a stripline
Jackman, Fourie (2017) DOI: 10.1109/TASC.2016.2642590

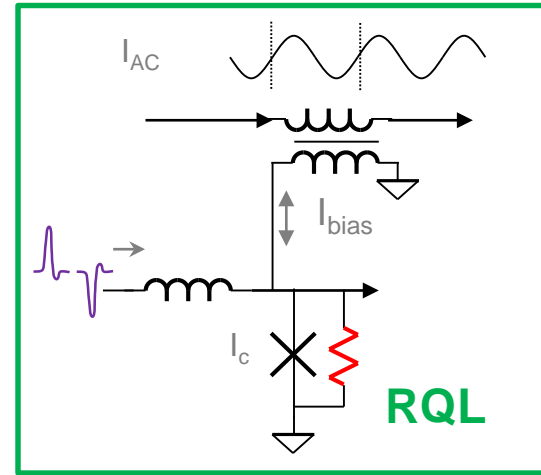
- RSFQ was the original, high-speed SFQ logic (770 GHz small circuit)
- New SFQ logic with no static power dissipation
- Each has merits



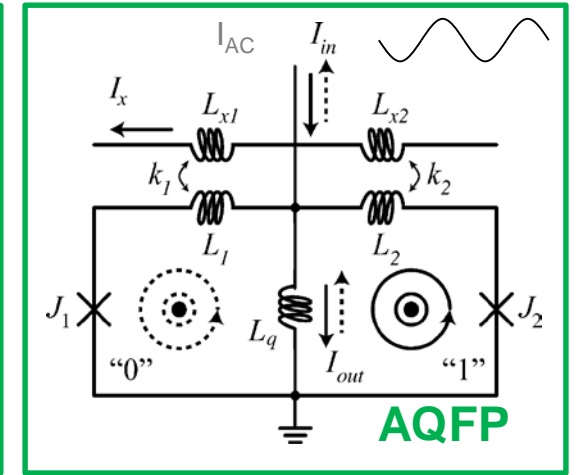
Rapid Single Flux Quantum



Energy-efficient Rapid Single Flux Quantum (Hypres)

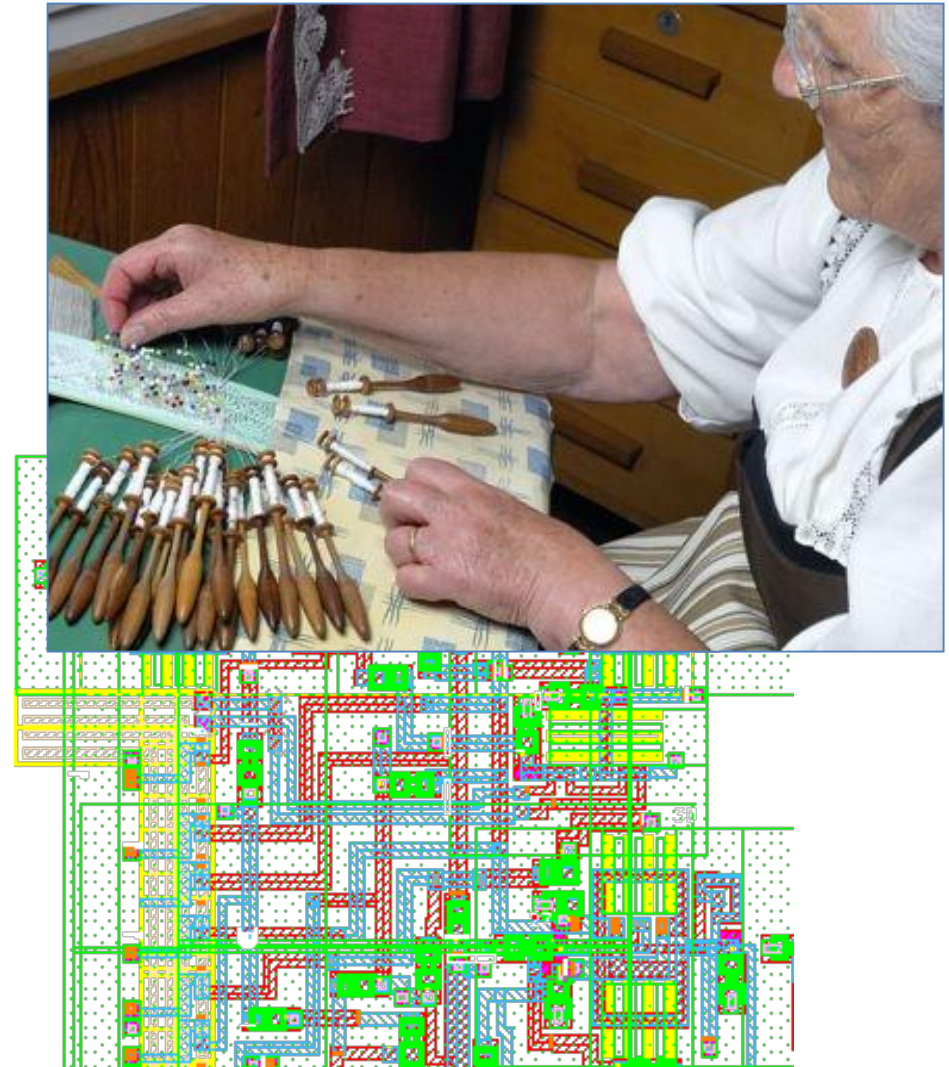


Reciprocal Quantum Logic (NGC)



Adiabatic Quantum Flux Parametron (Yokohama Nat. U.)

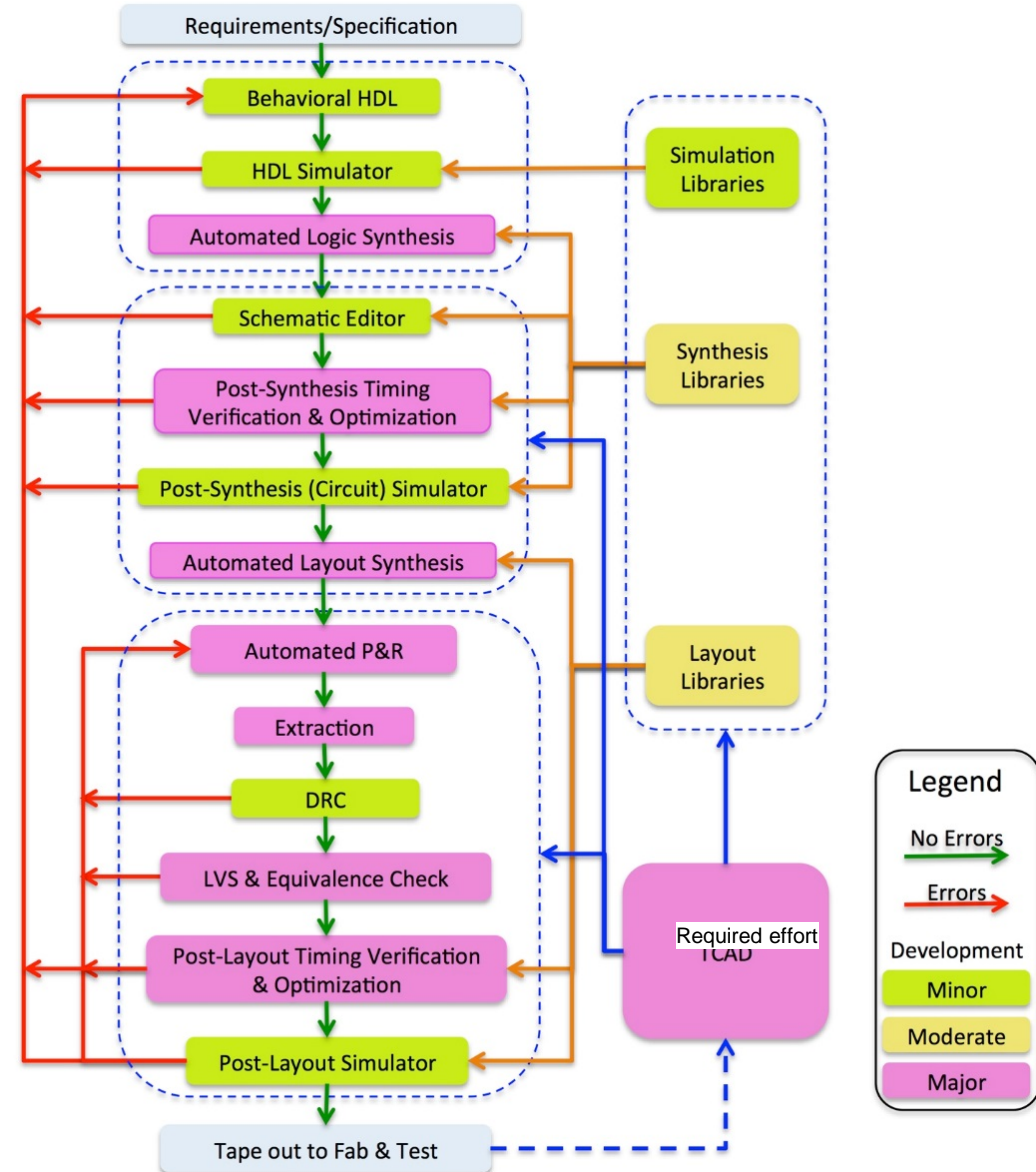
- Electronic design automation (EDA) tools missing or needing improvement:
 - Inductance extraction
 - Placement and routing (inductance range)
 - Synthesis
 - Timing analysis
 - Simulation
 - PDKs (not provided by foundry!)
- SFQ designers
 - No classes in the USA
 - Few designers



“Manual design is like making lace.” (SFQ designer)

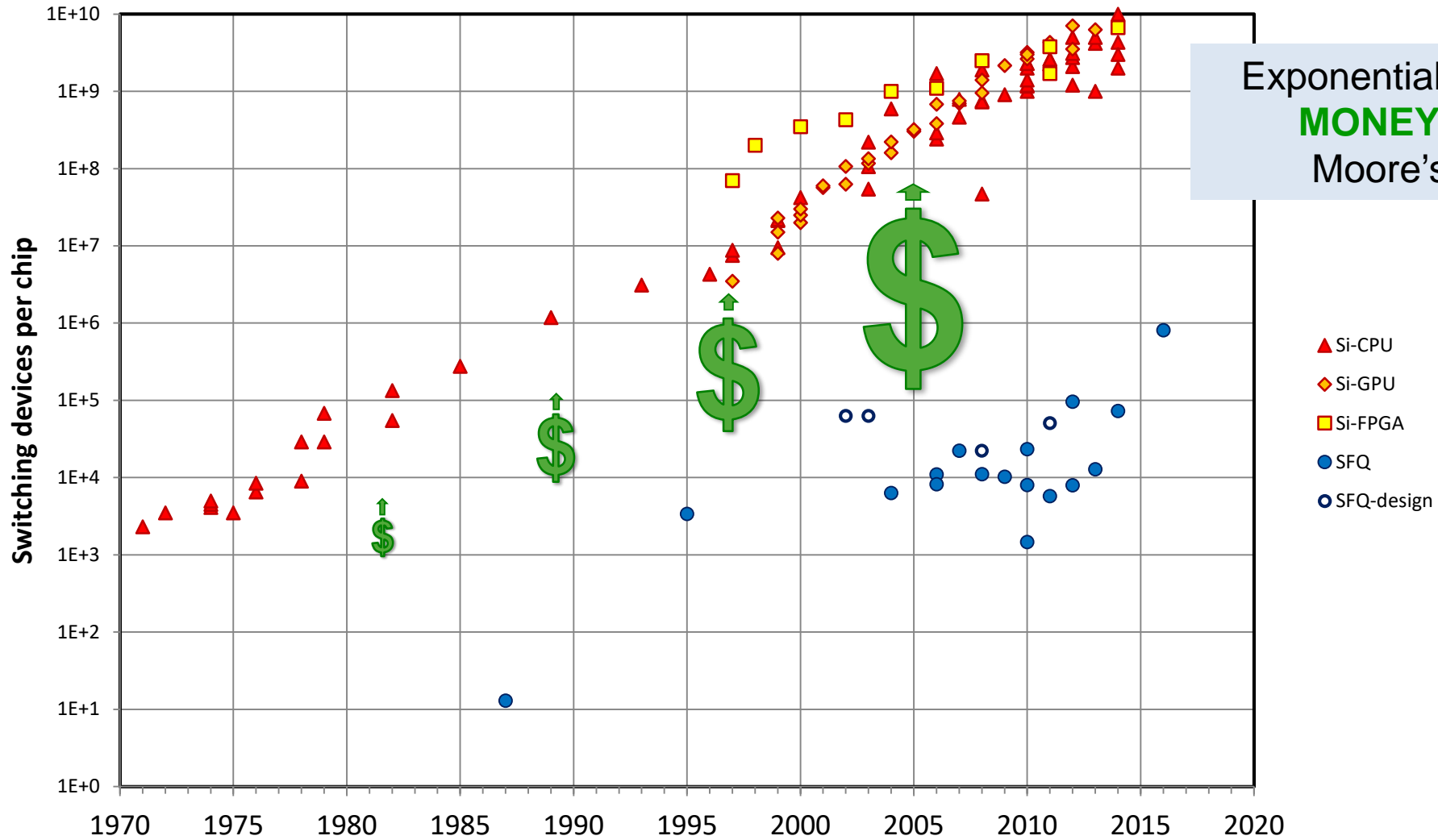
- Design, analysis, and verification tools need to be developed into a comprehensive EDA tool set specific to **very large scale superconductor integrated circuits**.
- SuperTools Program (IARPA)
 - Mark Heiligman, Program Manager
 - Started in 2017

SCE = Superconductor Electronics
 EDA = Electronic Design Automation
 HDL = Hardware Description Language
 P&R = Place-and-Route
 DRC = Design Rule Check
 LVS = Layout versus Schematic
 TCAD = Technology CAD





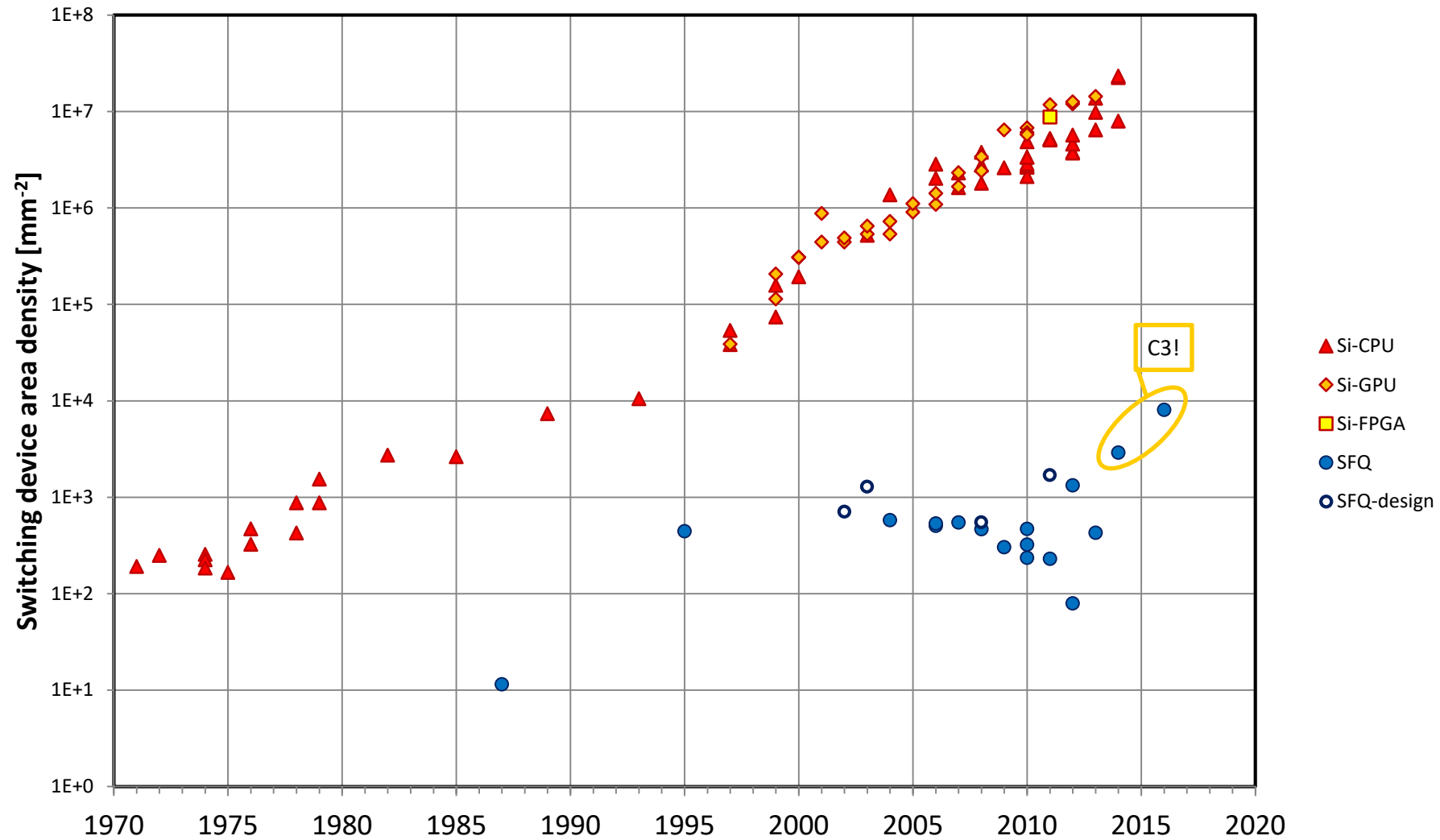
Complexity: SFQ lags semiconductors by $\sim 10^4$



Nagy et al. (2013) **Statistical Basis for Predicting Technological Progress**. DOI: 10.1371/journal.pone.0052669



Density: SFQ lags semiconductors by $\sim 10^4$





Can superconductor computing compete?



Shadow of the Colossus/
Wander to Kyojō
SCEI



A better way to view the relationship

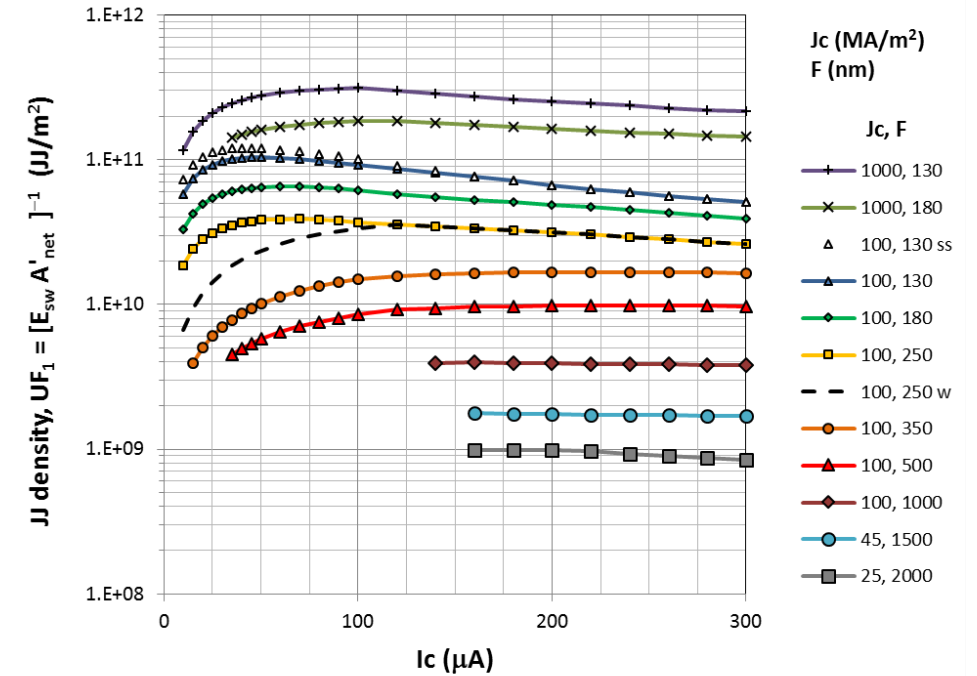
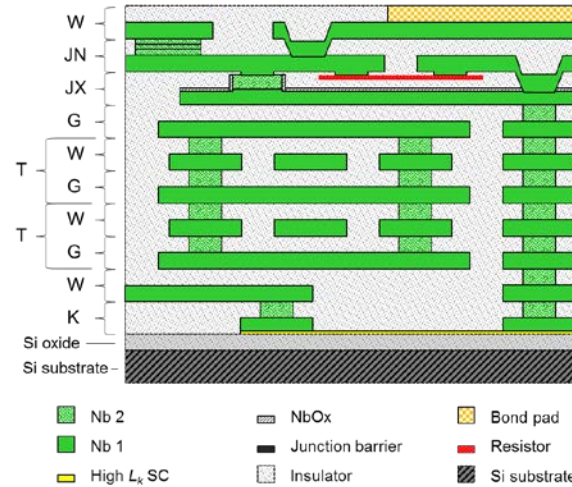
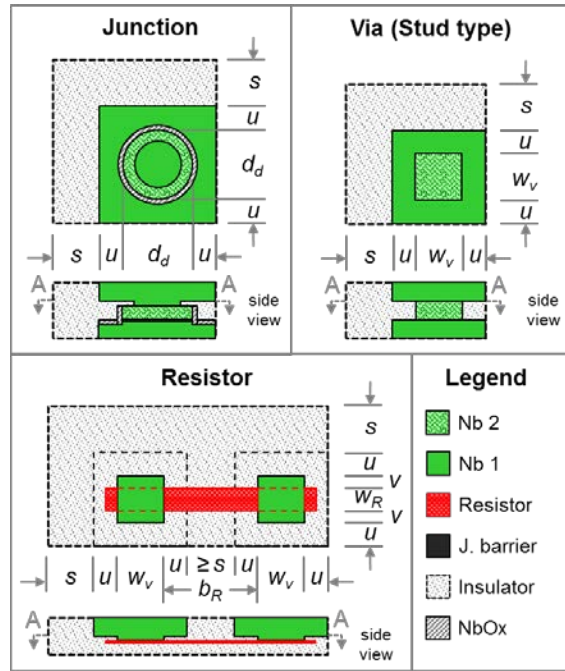


CMOS

SFQ 



Future Prospects



• Conclusions:

- Going beyond 10¹¹ JJ/m² (10⁷ JJ/cm²) requires significant changes
- Co-development of designs and processes is needed

- Conditions for adequate supercurrent
 - $W \sim \xi$
 - $L < 3\xi$
- Normal state resistance affects switching speed and energy dissipated in the weak link
 - Fastest switching with $\beta_c \sim 1$
 - Material can be different in the weak link

| Material | T_c [K] Bulk | Coherence length, ξ [nm] | Mag. pen. depth, λ_L [nm] | J_c [mA/ μm^2] | Crystal structure |
|------------------|-------------------|------------------------------|-----------------------------------|------------------------------|-------------------|
| Al | 1.18 | 1600 | 16 | | fcc, A1 |
| MgB ₂ | 39 | 3.7-12 ab 1.6-3.6 c | 85-180 | | C32 |
| MoGe | 7.4 | | | 12 (250 mK) | amorphous |
| MoSi | 7.5 | | | 11-25 (1.7 K) | amorphous |
| Nb | 9.2 | 38 | 90 | | bcc, A2 |
| NbN | 16 | 5 | 270 | 20-40 (4.2 K) | cubic, B1 |
| NbTiN | 12-16 | | | | |
| NbSi | 3.1 | | | 0.14 (300 mK) | amorphous |
| NbTi | 9.0 | 5 | 150 | | |

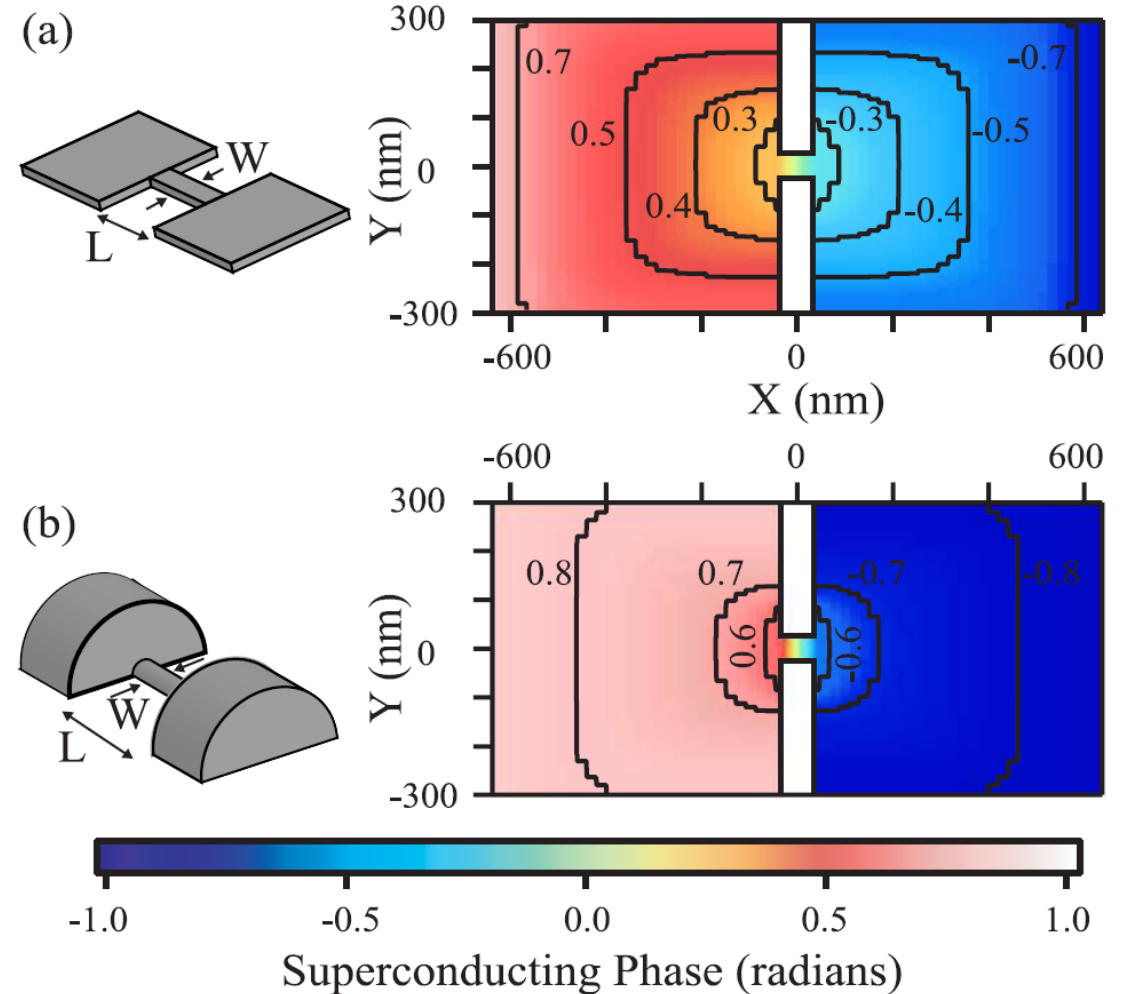
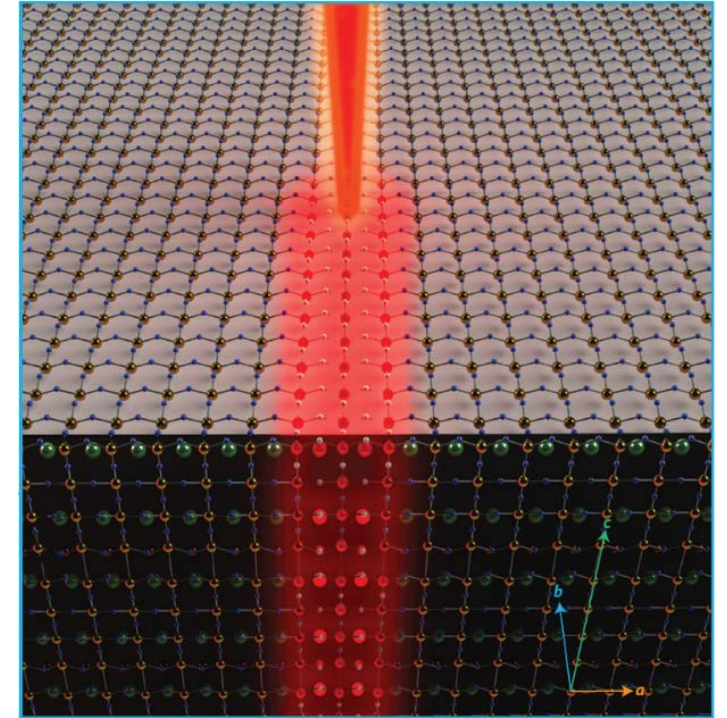
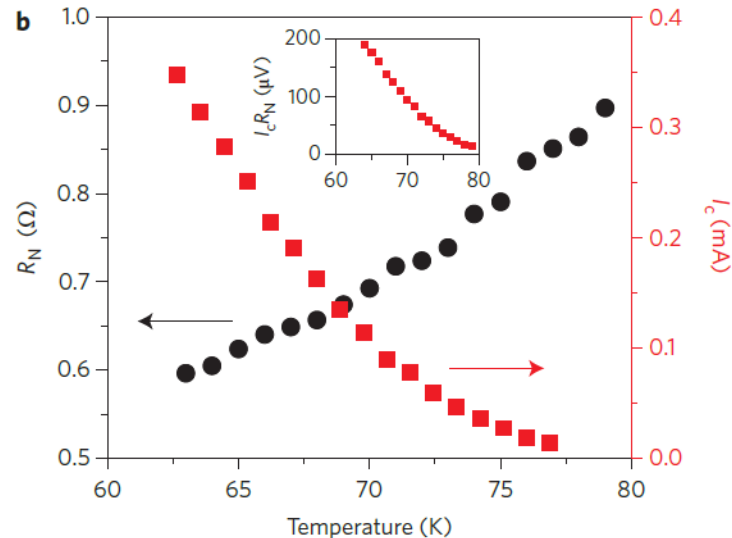
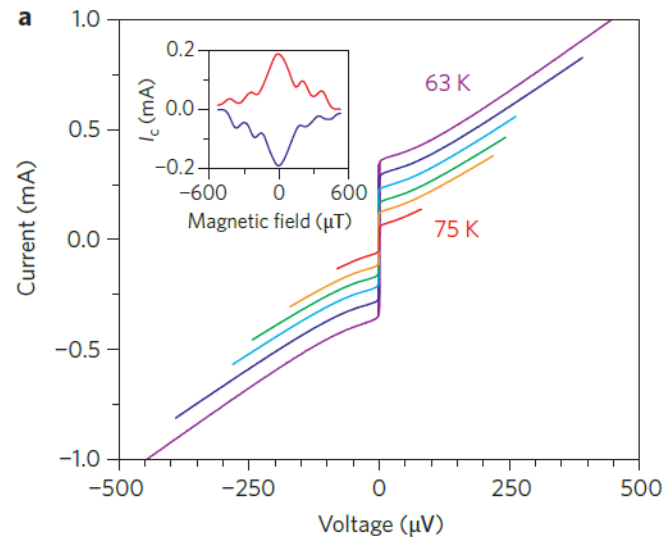


FIG. 2. Superconducting phase (color) as a function of position for an Al nanobridge with $L = 75$ nm and $W = 45$ nm. Vijay et al., 2009, DOI:10.1103/PhysRevLett.103.087003

Nano Josephson superconducting tunnel junctions in $\text{YBa}_2\text{Cu}_3\text{O}_{7-\delta}$ directly patterned with a focused helium ion beam

Shane A. Cybart^{1,2*}, E. Y. Cho¹, T. J. Wong¹, Björn H. Wehlin¹, Meng K. Ma¹, Chuong Huynh³ and R. C. Dynes^{1,2}





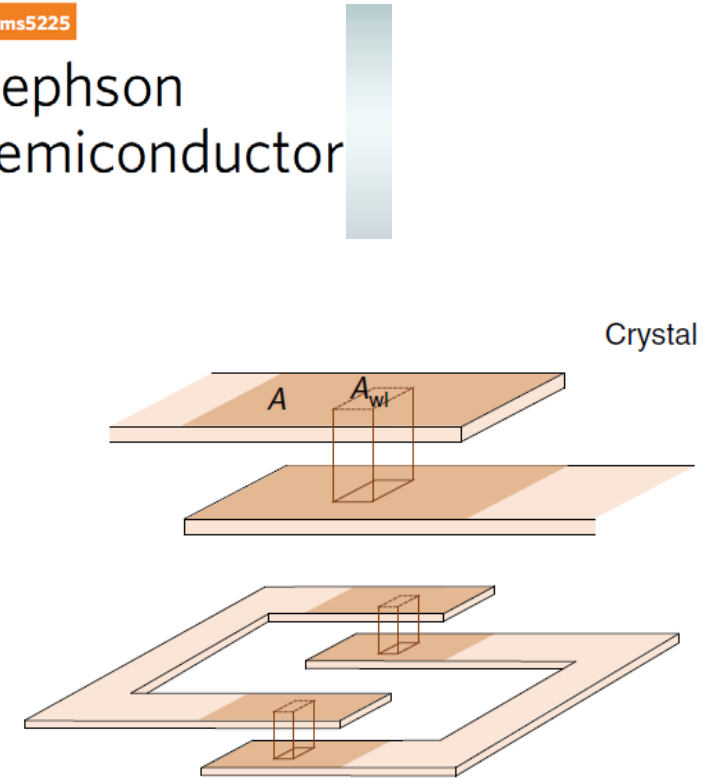
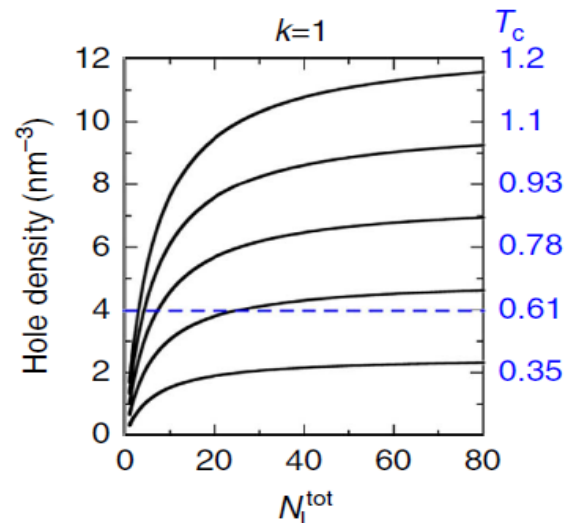
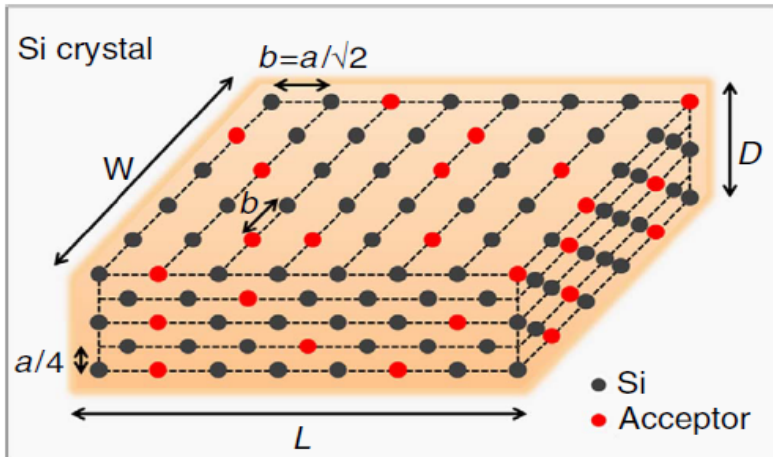
Received 11 Oct 2013 | Accepted 28 May 2014 | Published 2 Jul 2014

DOI: 10.1038/ncomms5225

Bottom-up superconducting and Josephson junction devices inside a group-IV semiconductor

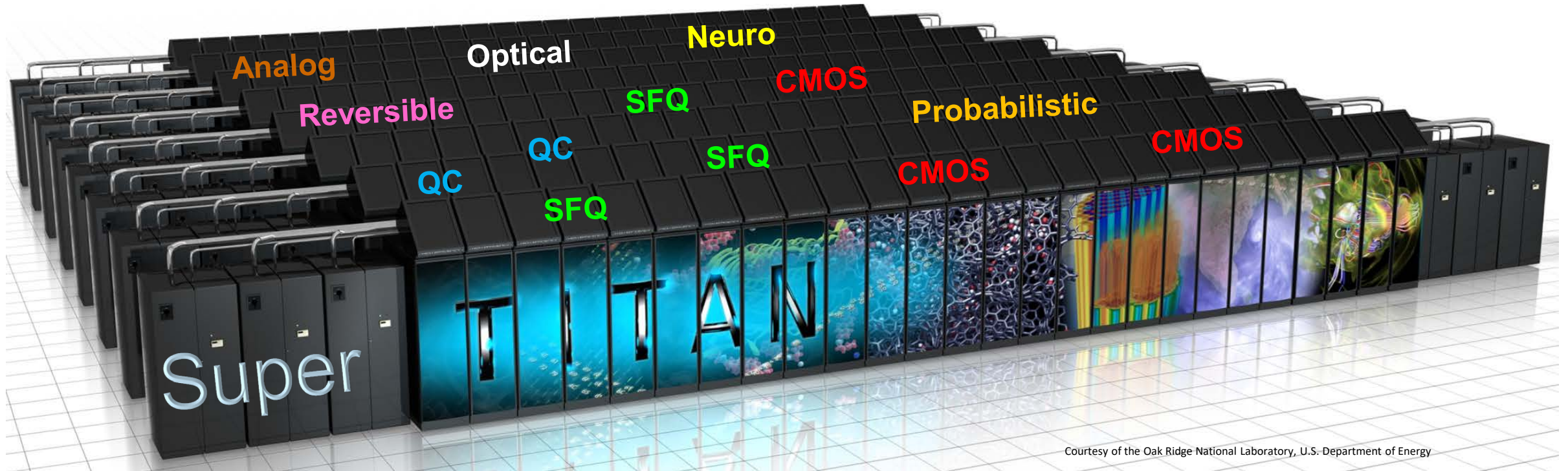
Yun-Pil Shim^{1,2} & Charles Tahan¹

- Concept paper
- Superconducting devices formed in single crystal Si (or Ge)
- Atomistic fabrication techniques and precision hole-doped regions





Future Supercomputing Vision



Courtesy of the Oak Ridge National Laboratory, U.S. Department of Energy

- Hybrid technologies: digital (CMOS, SFQ), probabilistic, analog, neuromorphic, reversible, and quantum computing (QC)
— whatever works best!
- SFQ digital platform supports multiple cryogenic technologies
- Requires optical interconnects between room temperature and cryogenic nodes

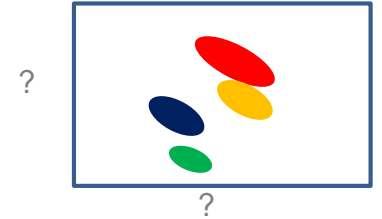
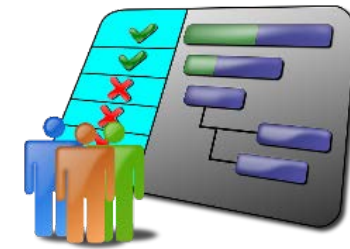


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Lessons from an Emerging Technology

- Fair **metrics** are needed to evaluate alternative computing technologies
 - level the playing field to allow different technologies to compete
 - relevant lessons from hiring for diversity?
- Ramping up requires time **and resources**
 - the real Moore's Law
- Government funding alone is not sufficient
 - cost to develop energy-efficient, large-scale computers is large
 - ramp up using smaller products and markets
- Don't go it alone
 - use your mother elephant
- Go big or go home!
 - small improvements are not worth the effort
 - large disruptions require even larger advantages





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